

# MOS Model 11

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# Introduction : MOS Model 11

## Goals for MOS Model 11:

- suitable for digital, analog and RF
- number of parameters comparable to MM9
- simulation time comparable to MM9
- physics based

# Introduction : MOS Model 11 (II)

**Model developed for accurate distortion analysis in circuit design:**

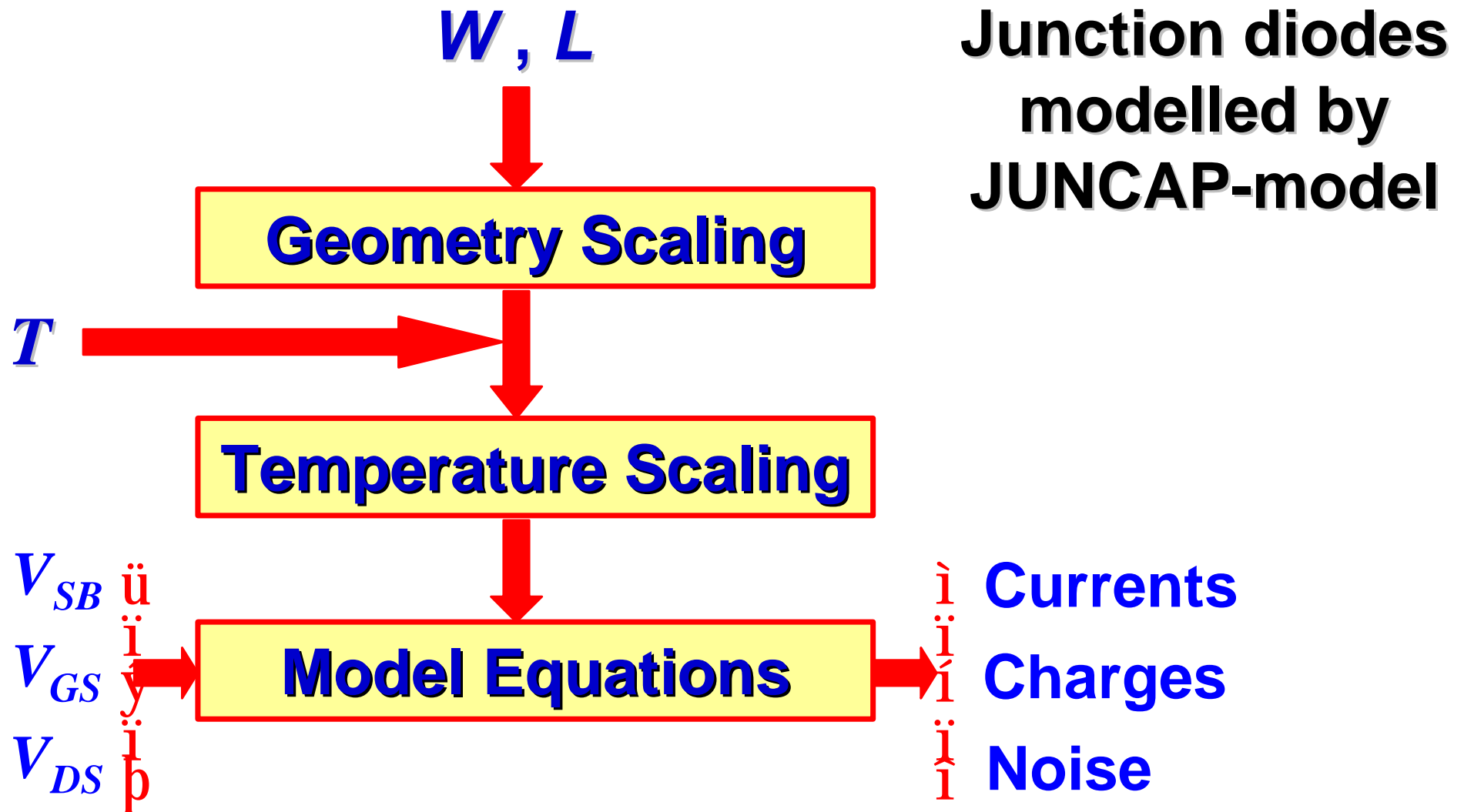
- **surface-potential-based model**
  - ⇒ accurate transition weak → strong inversion
- **symmetrical**
- **distortion**
  - ⇒ accurate description of third-order derivatives  
(i.e.  $\partial^3 I / \partial V^3$ )

# Introduction : MOS Model 11 (III)

## Implemented physical effects:

- mobility reduction
- bias-dependent series-resistance
- velocity saturation
- conductance effects (CLM, DIBL, etc.)
- gate leakage current
- gate depletion
- quantum-mechanical effects
- bias-dependent overlap capacitances

# Introduction : Structure of MOS Model 11



# Outline

- **Introduction**
- **DC-Model**
- **AC-Model**
- **Noise Model**
- **Model Parameters & Extraction**
- **Examples & Applications**
- **Conclusions**

# Outline : DC-Model

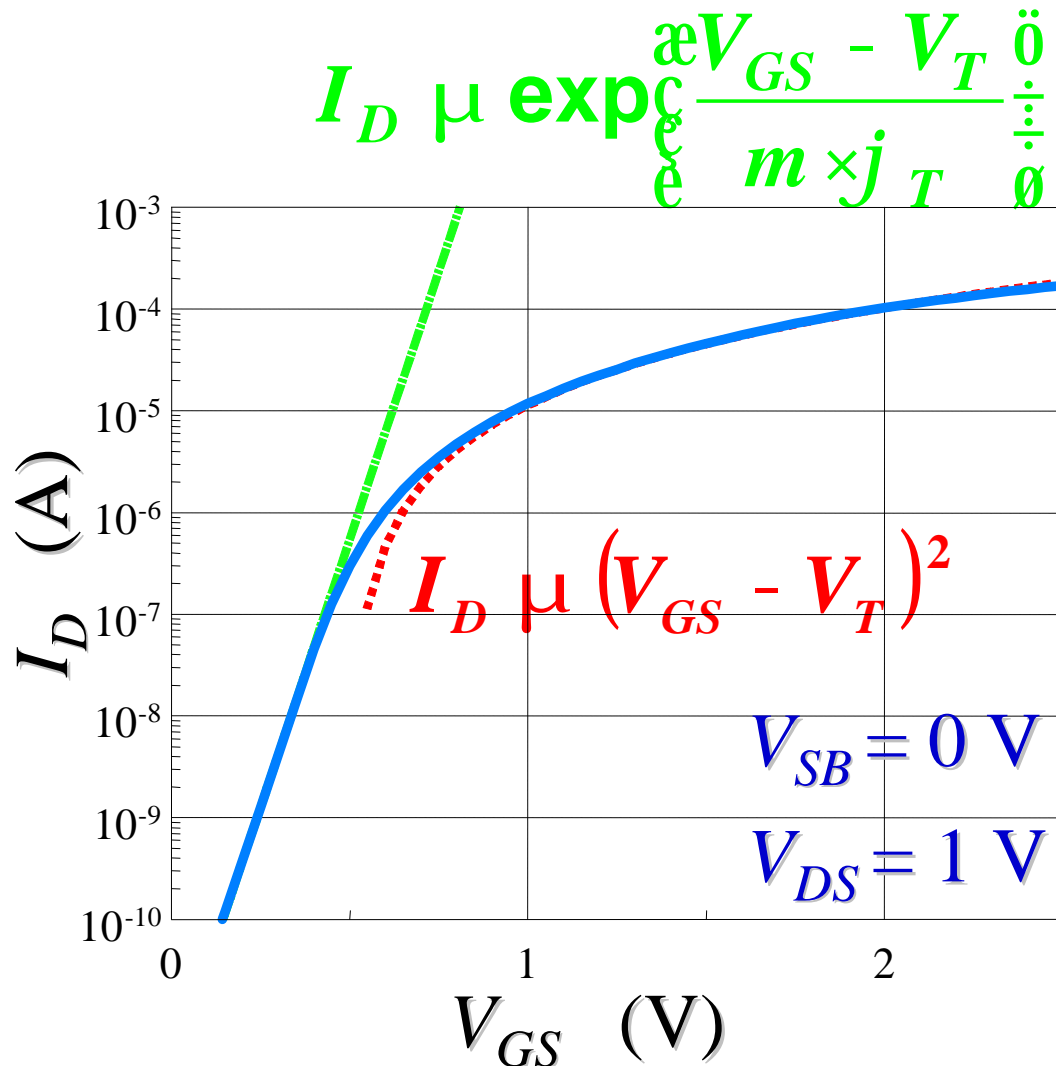
- $V_T$  vs.  $y_s$ -based models
- Mobility reduction
- Bias-dependent series-resistance
- Velocity saturation
- Conductance effects
- Symmetry
- Gate leakage current
- Junction model

# DC-Model : $V_T$ -based model

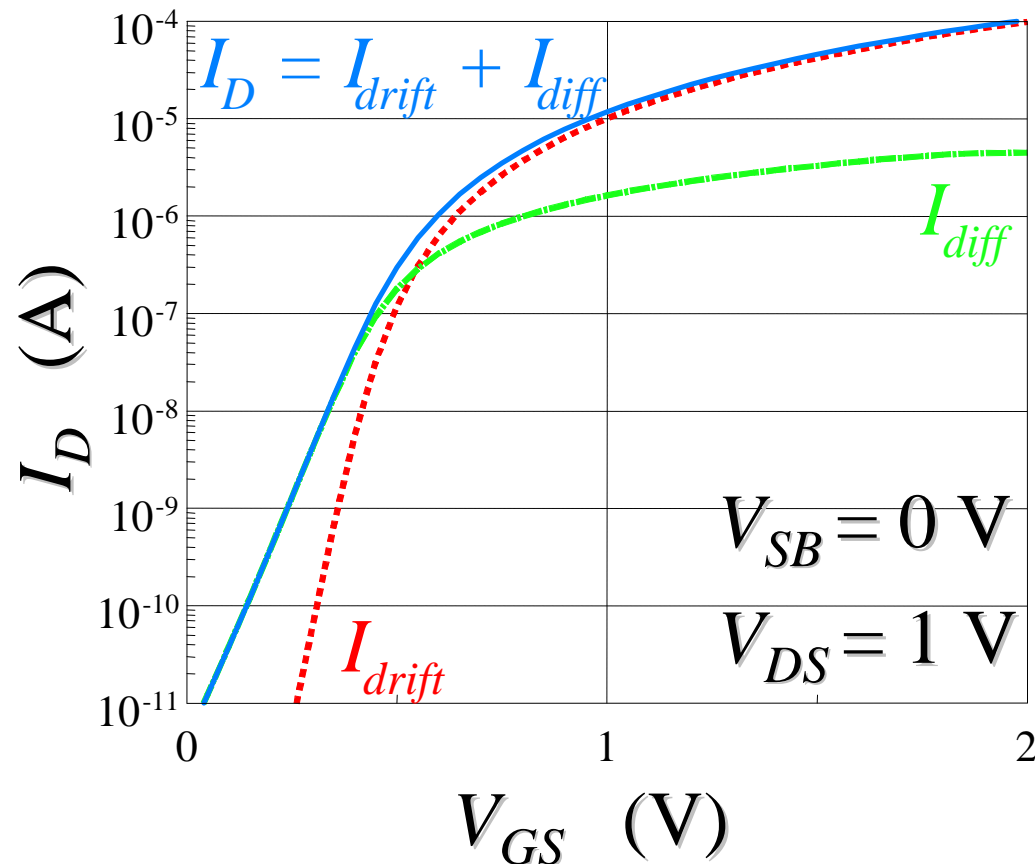
## $V_T$ -based model:

Interpolation needed  
between subthreshold  
and superthreshold  
(e.g. BSIM4 and MM9)

⇒ Smoothing function



# DC-Model : Surface-Potential-Based Model



## $y_s$ -based model:

Single equation for whole operation range:

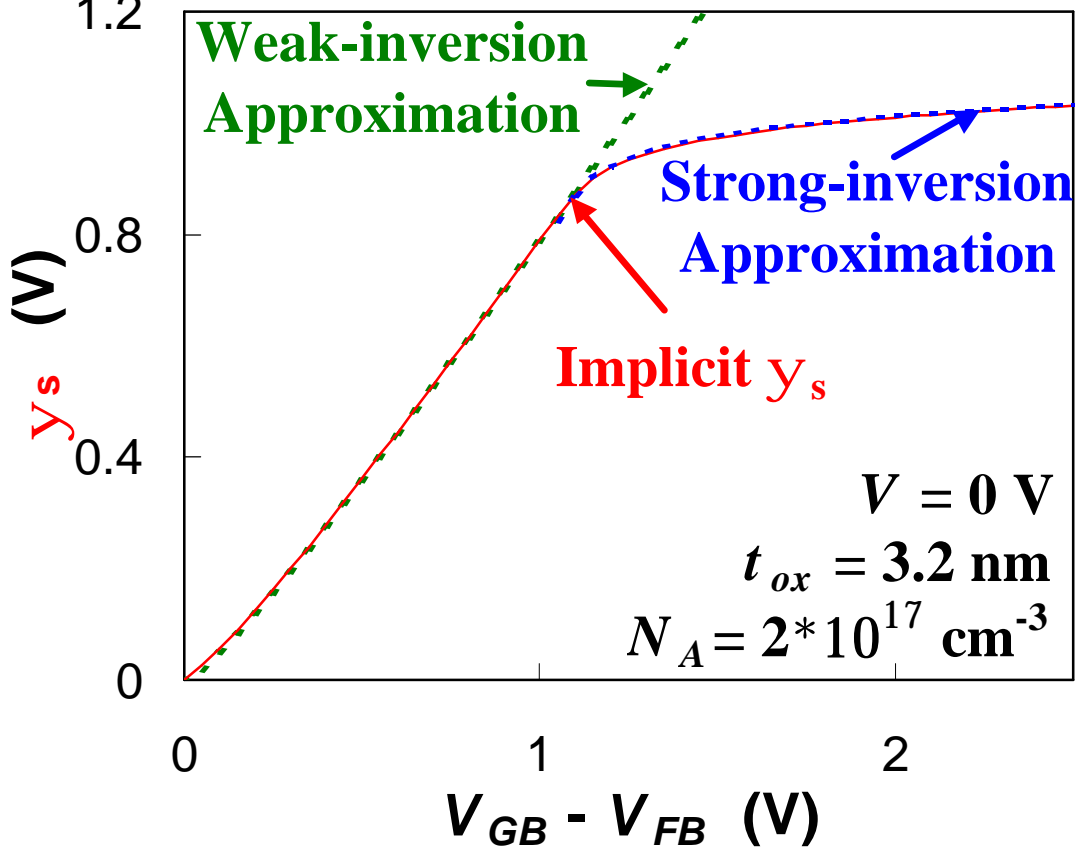
$$I_{drift} = f(V_{GB}, y_{s0}, y_{sL})$$

$$I_{diff} = g(V_{GB}, y_{s0}, y_{sL})$$

$$I_D = I_{drift} + I_{diff}$$

# DC-Model : Surface Potential Approximation

$$\frac{\partial}{\partial y_s} \left( \frac{V_{GB} - V_{FB} - y_s}{k} \right)^2 = y_s + j_T \times e^{-\frac{2j_F - V}{j_T}} \times \frac{\partial y_s}{\partial e^{j_T}} - 1 + j_T \times e^{-\frac{2j_F - V}{j_T}} \times \frac{\partial y_s}{\partial e^{j_T}} - 1$$



- ⇒ Iterative solution
- ⇒ Time consuming??
- ⇒ Approximation used:  
 $y_s = y_s(V_{GB}, V)$

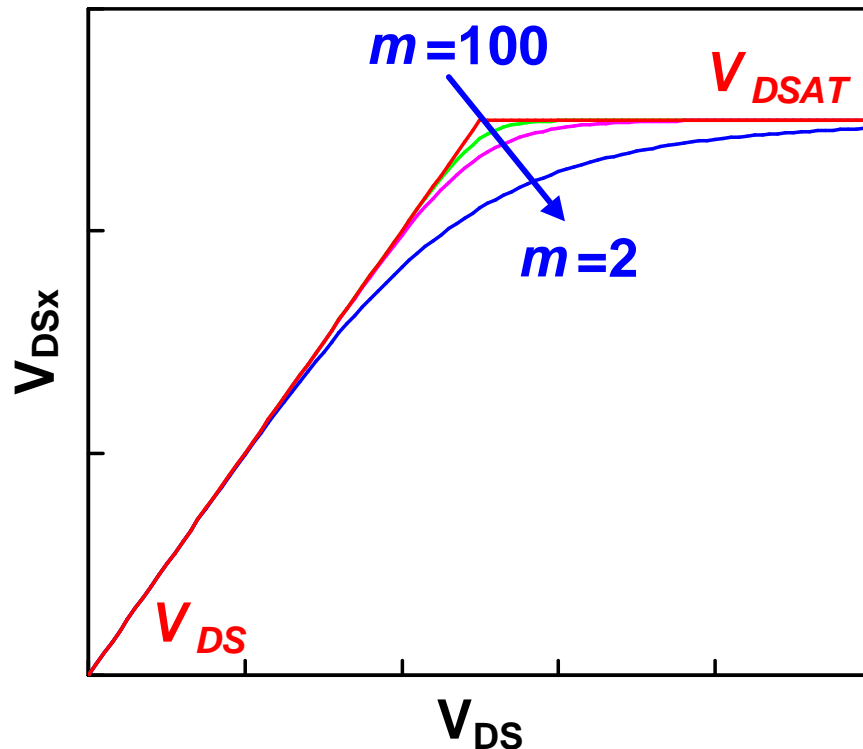
(Solid-State Electron. 44, 2000)

# DC-Model : Surface Potential Approximation (II)

Model incorporates linear/saturation region

for long-channel case:  $V_{DSAT} = V_{DSAT_{long}}$

⇒ Short-channel devices:  $V_{DSAT} < V_{DSAT_{long}}$



Approximation used:

$$y_s = y_s(V_{GB}, V_{DSx} + V_{SB})$$

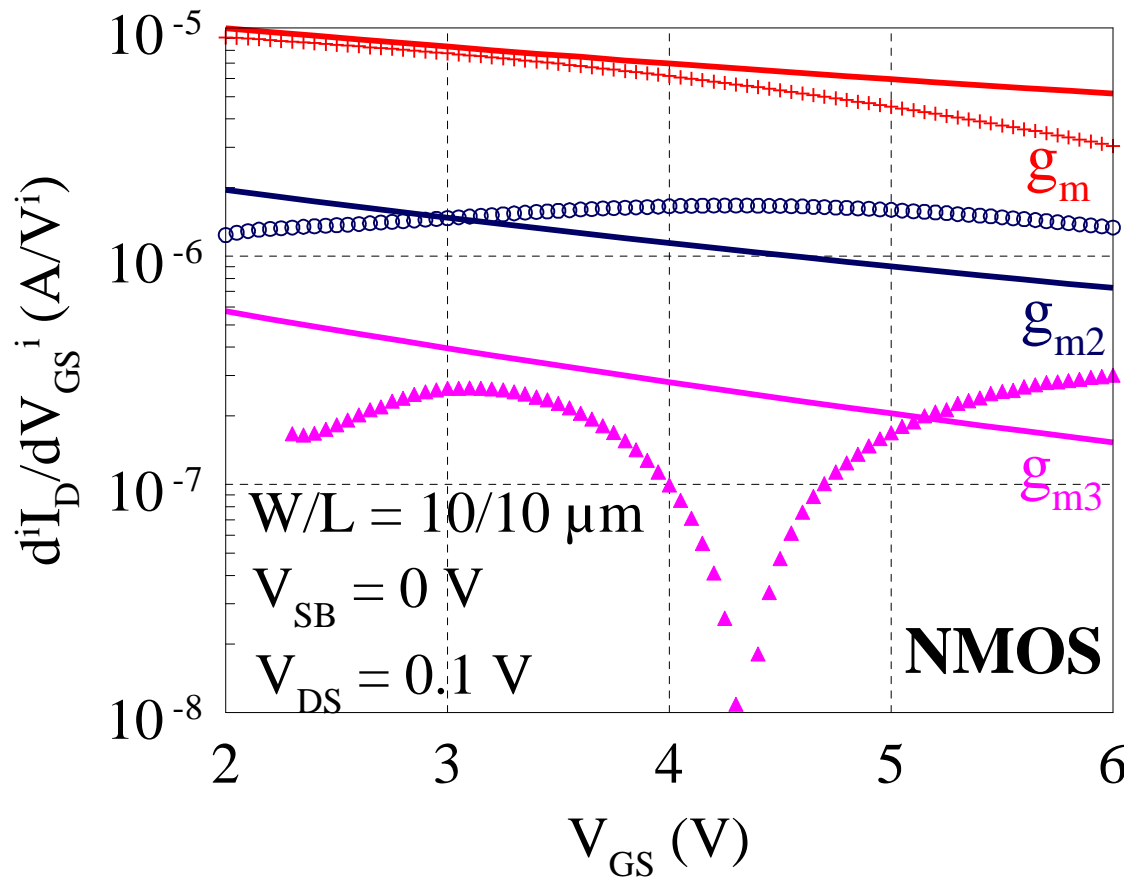
where:

$$V_{DSx} = \frac{V_{DS} \times V_{DSAT}}{\left( V_{DS}^{2m} + V_{DSAT}^{2m} \right)^{\frac{1}{2m}}}$$

(K. Joardar et al, IEEE TED-45, pp. 134-148, 1998)

# DC-Model : Mobility Reduction

**MOS Model 9:**  $m = \frac{m_0}{1 + q \times E_{eff}}$



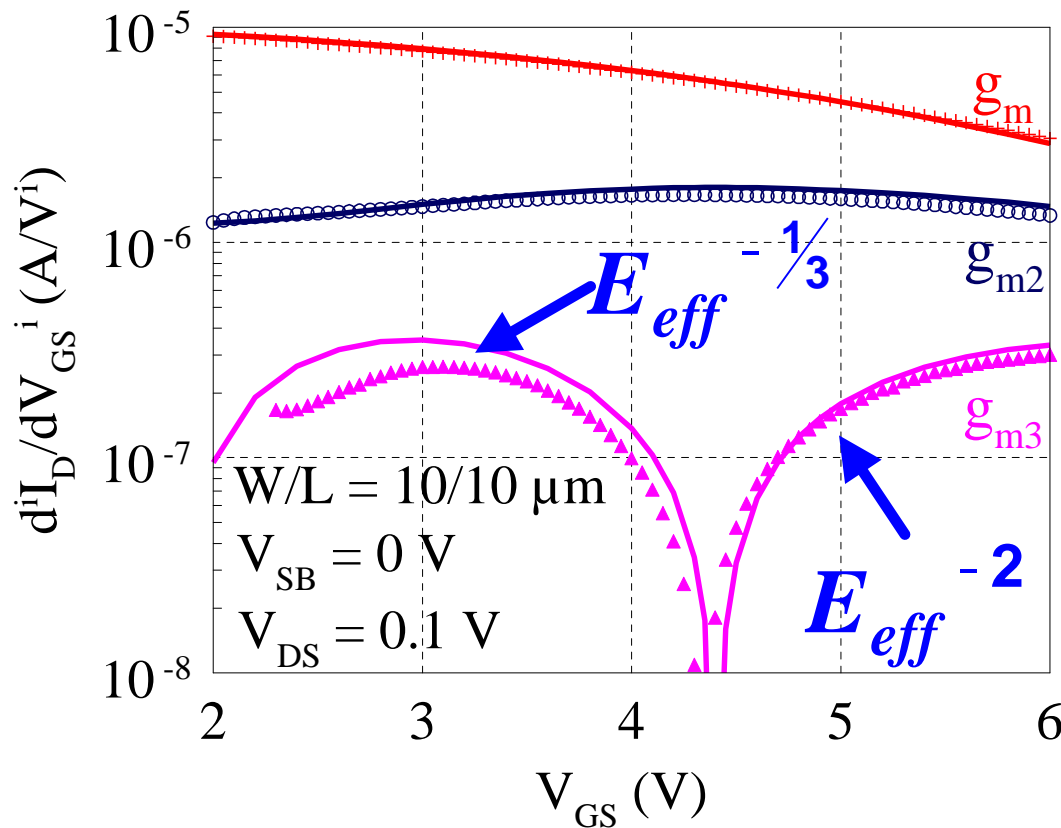
⇒ higher-order derivatives:

$$g_{mi} = \frac{\mathcal{I}^i I_D}{\mathcal{I} V_{GS}^i}$$

not well described

# DC-Model : Mobility Reduction (II)

- surface roughness scattering:  $m_{sr} \propto \mu E_{eff}^{-2}$
- phonon scattering:  $m_{ph} \propto \mu E_{eff}^{-1/3}$



$$m = \frac{m_0}{1 + \sqrt{q_{sr} \times E_{eff}^4 + q_{ph} \times E_{eff}^{2/3}}}$$

(IEEE TED-44, No. 11, pp. 2044-2052, 1997)

⇒ different for holes

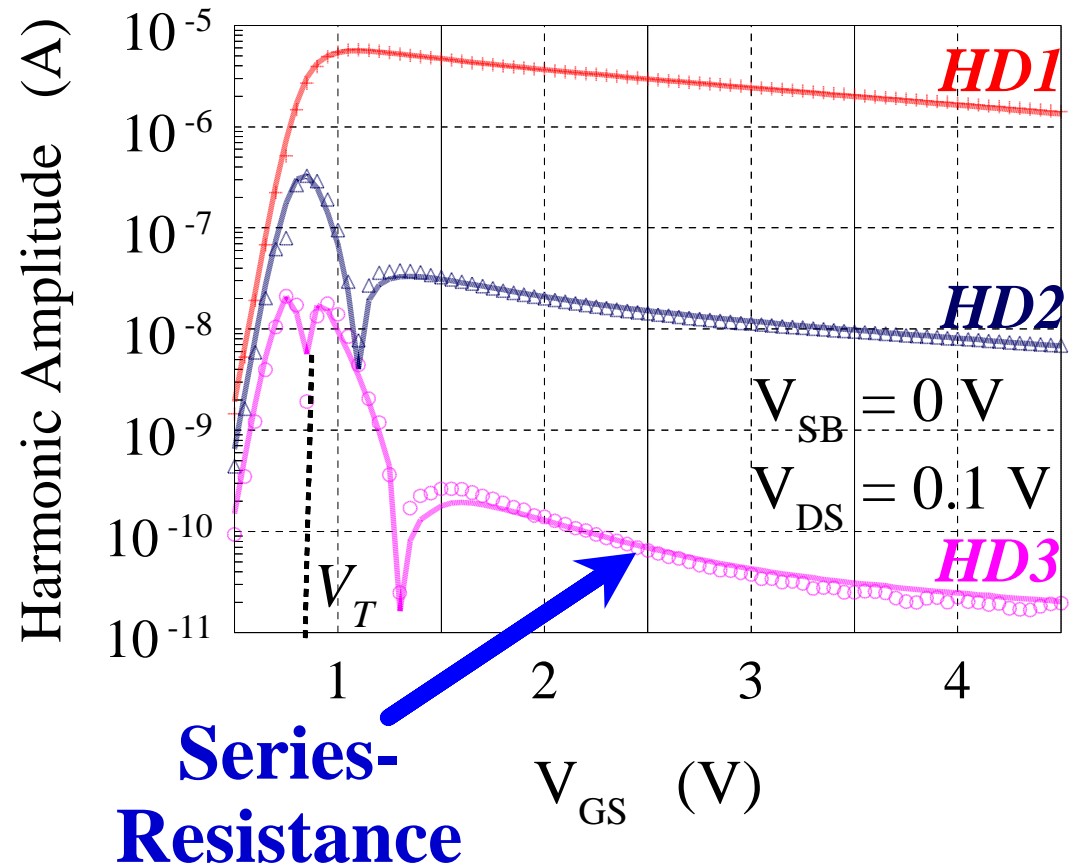
# DC-Model : Bias-Dependent Series-Resistance

## Internal series-resistance:

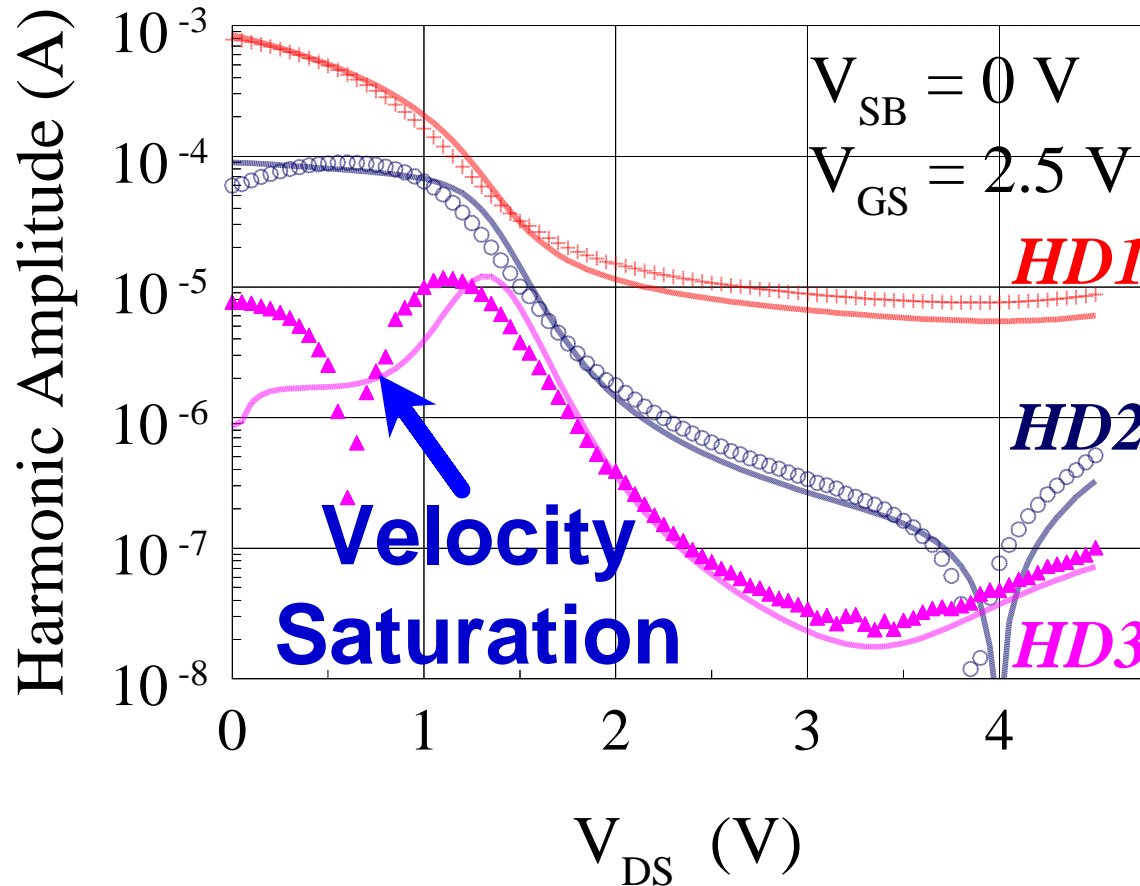
- bias-dependent for LDD-MOSFETs
- independent parameters:

$$q_R = 2 \times b \times R_{series}$$

Gate-bias induced distortion for NMOS  $W/L=10/1\mu\text{m}$



# DC-Model : Velocity Saturation



Drain-bias induced distortion  
 NMOS,  $W/L=10 \mu\text{m} / 1\mu\text{m}$

**Drain Current:**

$$I_D = -W \times Q_{inv} \times v$$

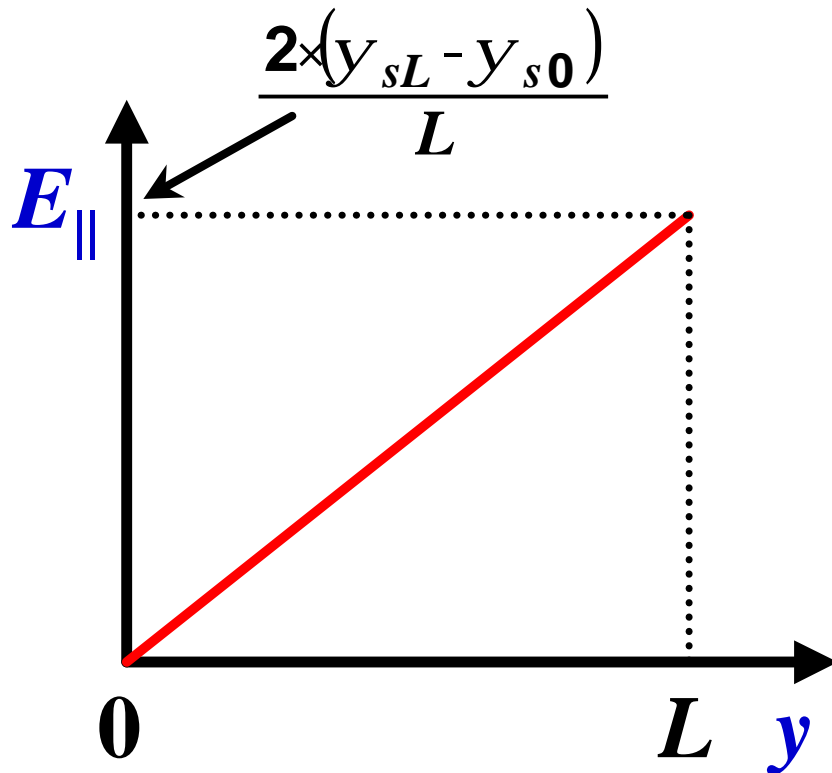
**Carrier Velocity (MM9, BSIM4):**

$$v = \frac{m \times E_{||}}{1 + \frac{m}{v_{sat}} \times E_{||}}$$

# DC-Model : Velocity Saturation (II)

Electron Velocity:

$$v = \frac{m \times E_{\parallel}}{\sqrt{1 + \frac{\hbar m}{e \times v_{sat}} \times E_{\parallel}}}$$

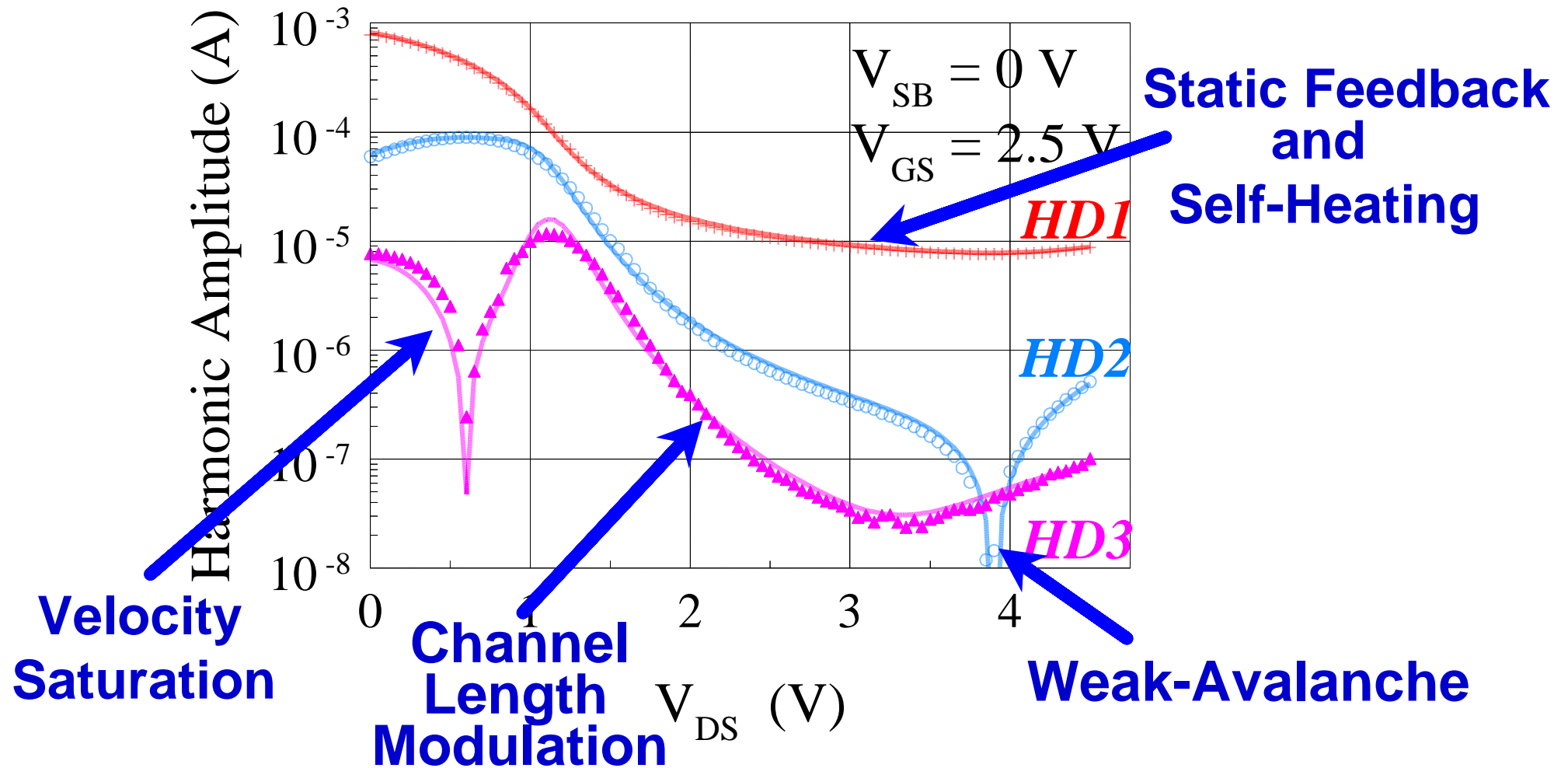


Approximation used in calculation of  $I_D$ :

Electric field  $E_{\parallel}$  varies linearly along channel

# DC-Model : Conductance Modelling

Drain-Bias Induced Distortion for NMOS W/L=10/1mm



## DC-Model : Symmetry

**Symmetry of MOSFET : Drain ↔ Source**

$$I_D( V_{GS}, V_{DS}, V_{SB} ) = -I_D( V_{GD}, V_{SD}, V_{DB} )$$

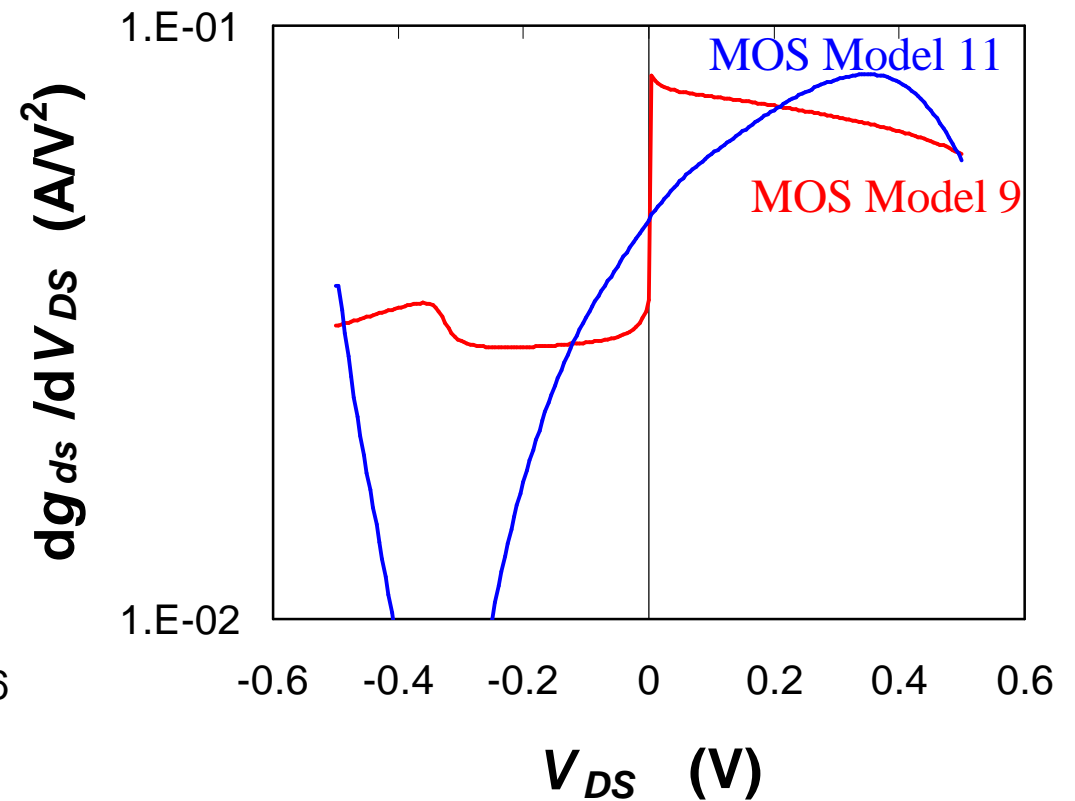
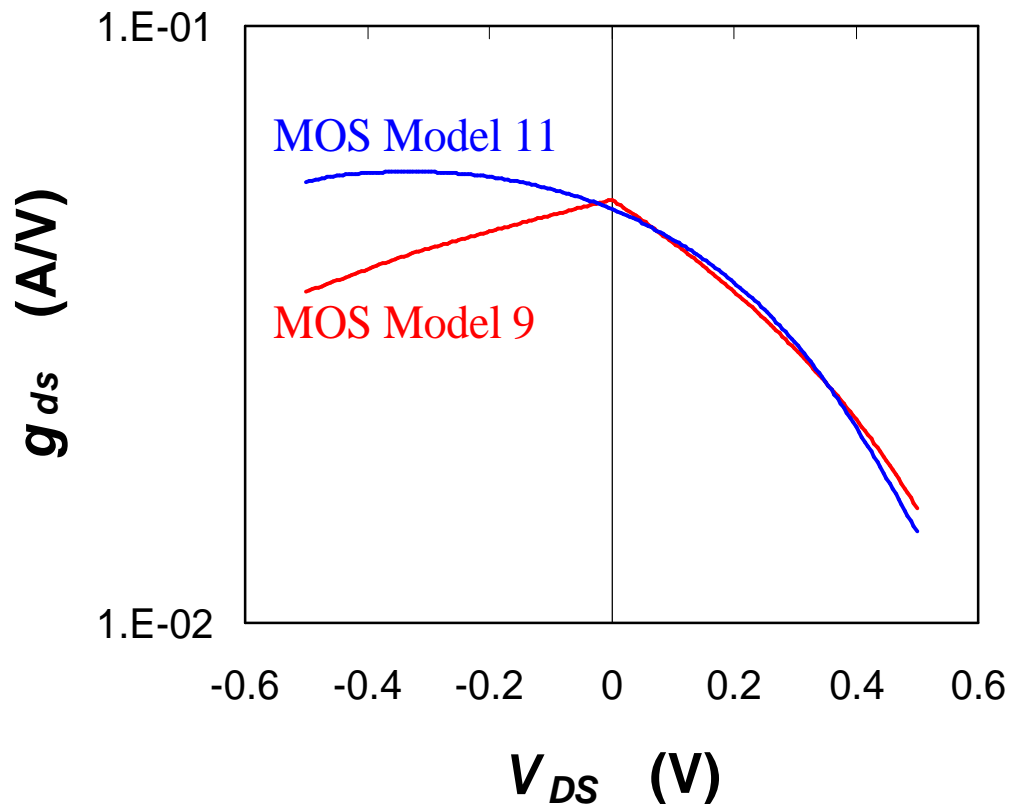
**Care has to be taken with the implementation of:**

- **ideal current equation**
- **velocity saturation**
- **DIBL/static feedback**
- **smoothing function  
(linear/saturation region)**

# DC-Model : Symmetry (II)

Symmetry of MOSFET : Drain  $\leftrightarrow$  Source

$$I_D(V_{GS}, V_{DS}, V_{SB}) = -I_D(V_{GD}, V_{SD}, V_{DB})$$



# DC-Model : Gate Leakage Model

NMOS (in inversion):

Gate current density:

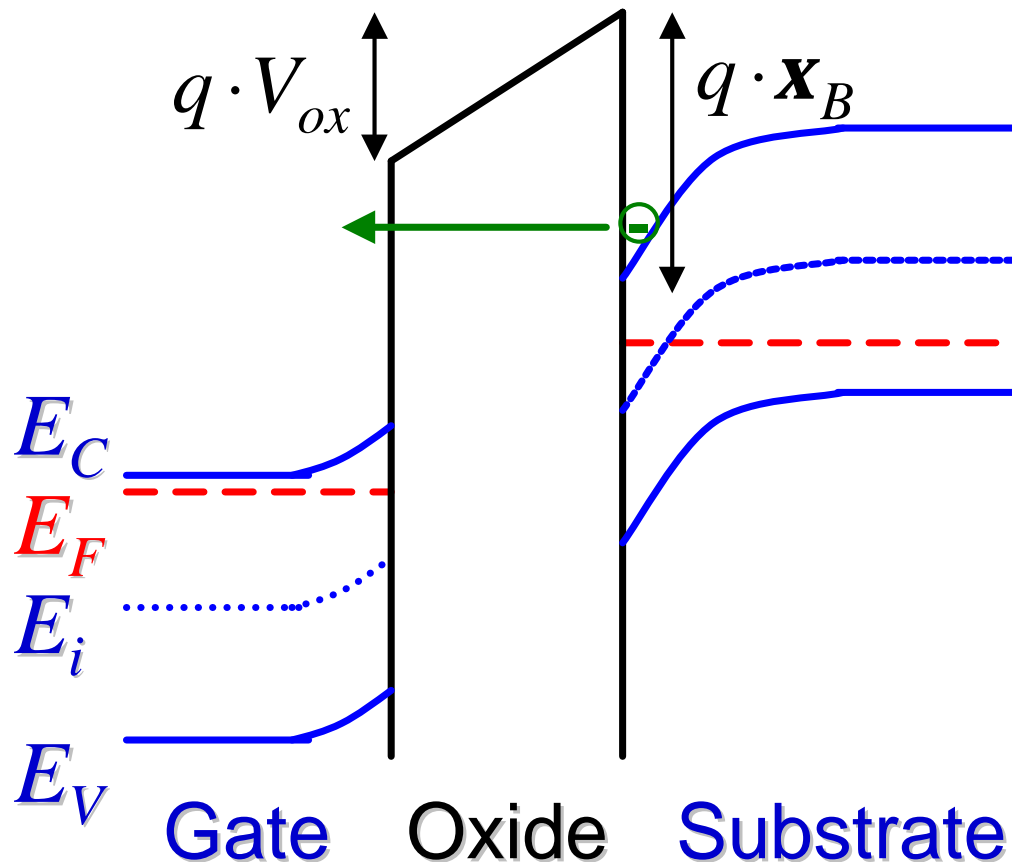
$$J_G \propto V_{ox} \cdot Q_{inv} \cdot P(V_{ox})$$

Direct-tunnelling probability:

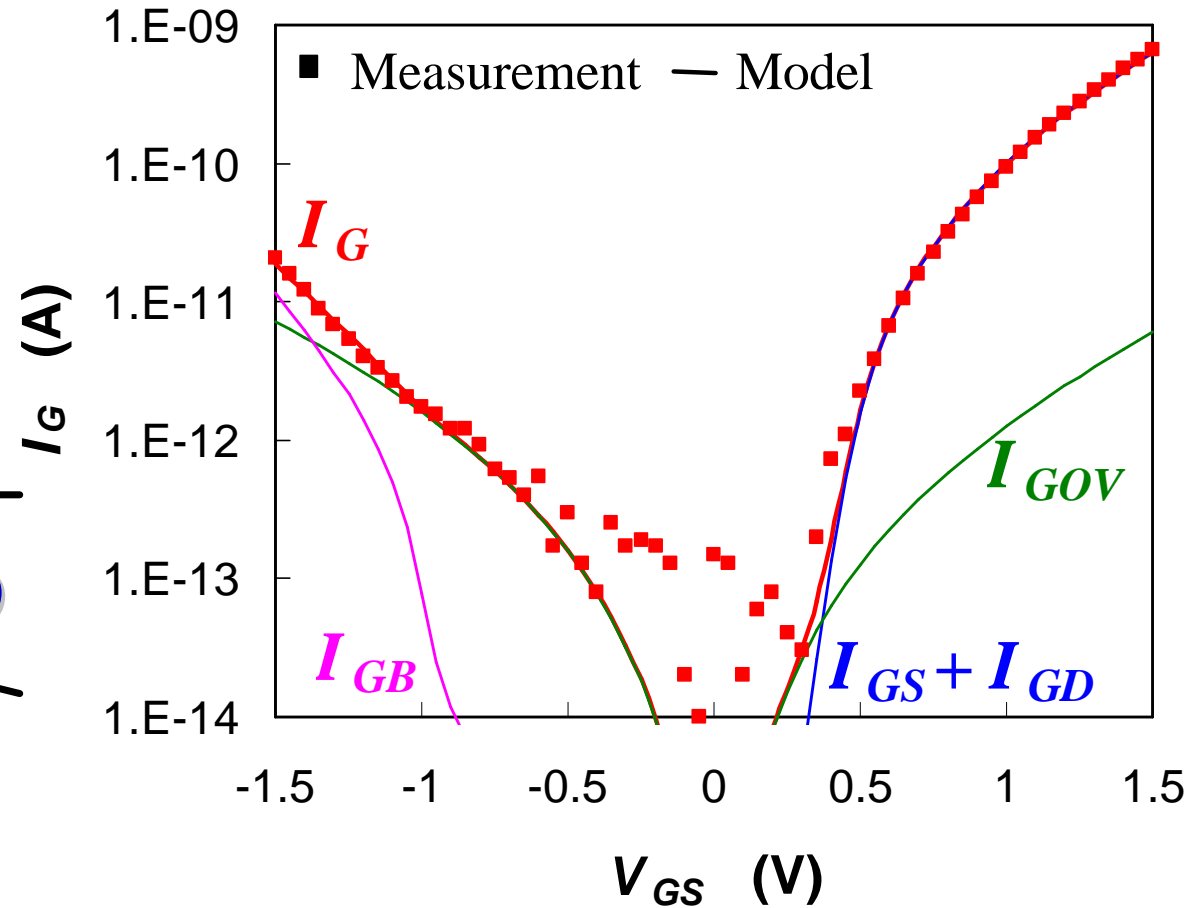
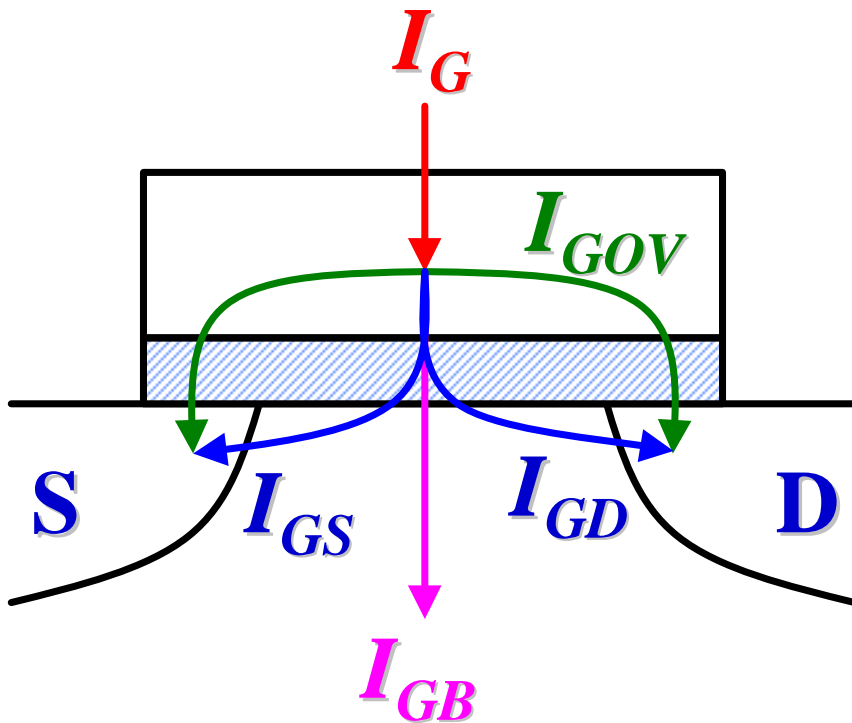
$$P(V_{ox}) = e^{-\frac{B}{V_{ox}} \cdot \left[ \left( 1 - \frac{V_{ox}}{x_B} \right)^{3/2} - 1 \right]}$$

Approximation (at  $V_{DS}=0$  V):

$$I_G = I_0 \cdot V_{ox} \cdot Q_{inv} \cdot e^{B_0 \cdot V_{ox}}$$



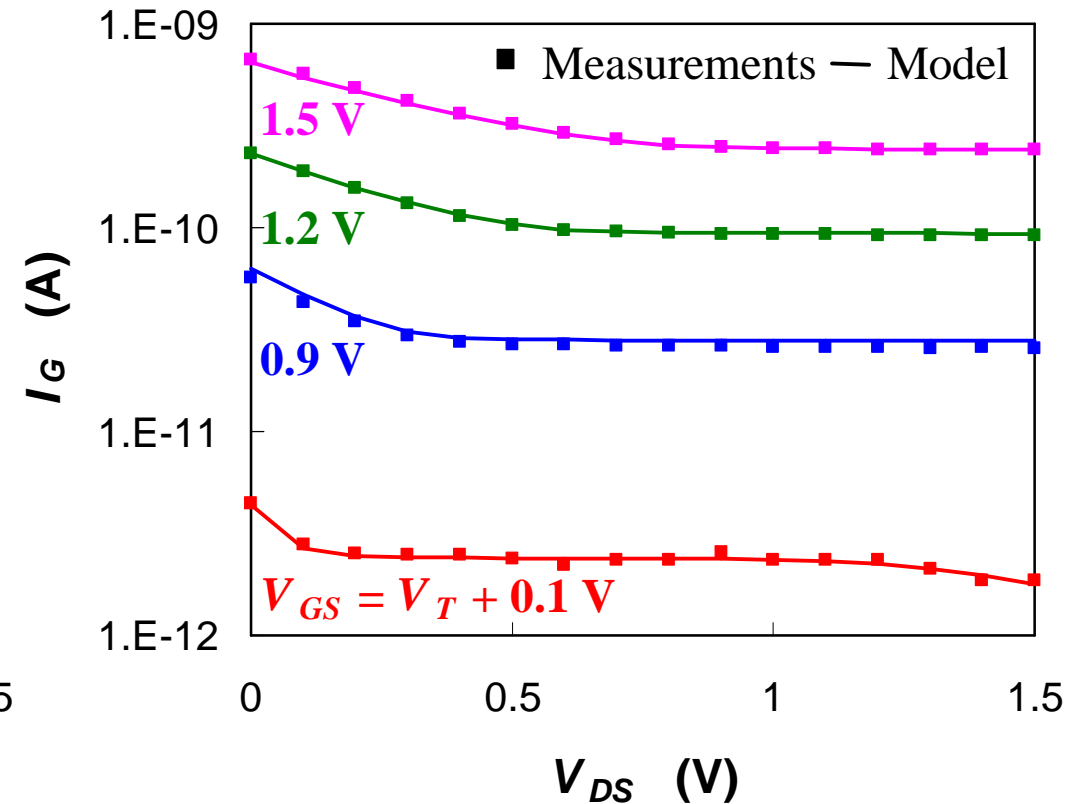
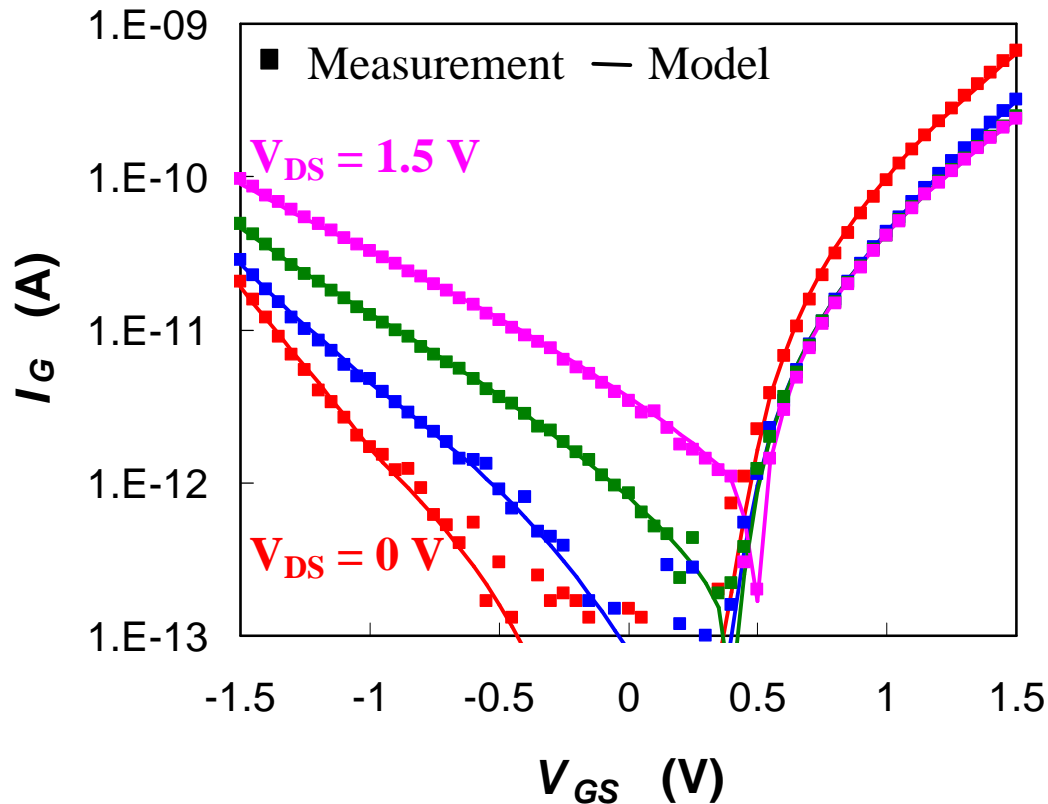
# DC-Model : Gate Leakage Model (II)



NMOS,  $V_{DS}=0$  V,  $t_{ox}=2$  nm,  $W/L=10/0.6\mu\text{m}$

# DC-Model : Gate Leakage Model (III)

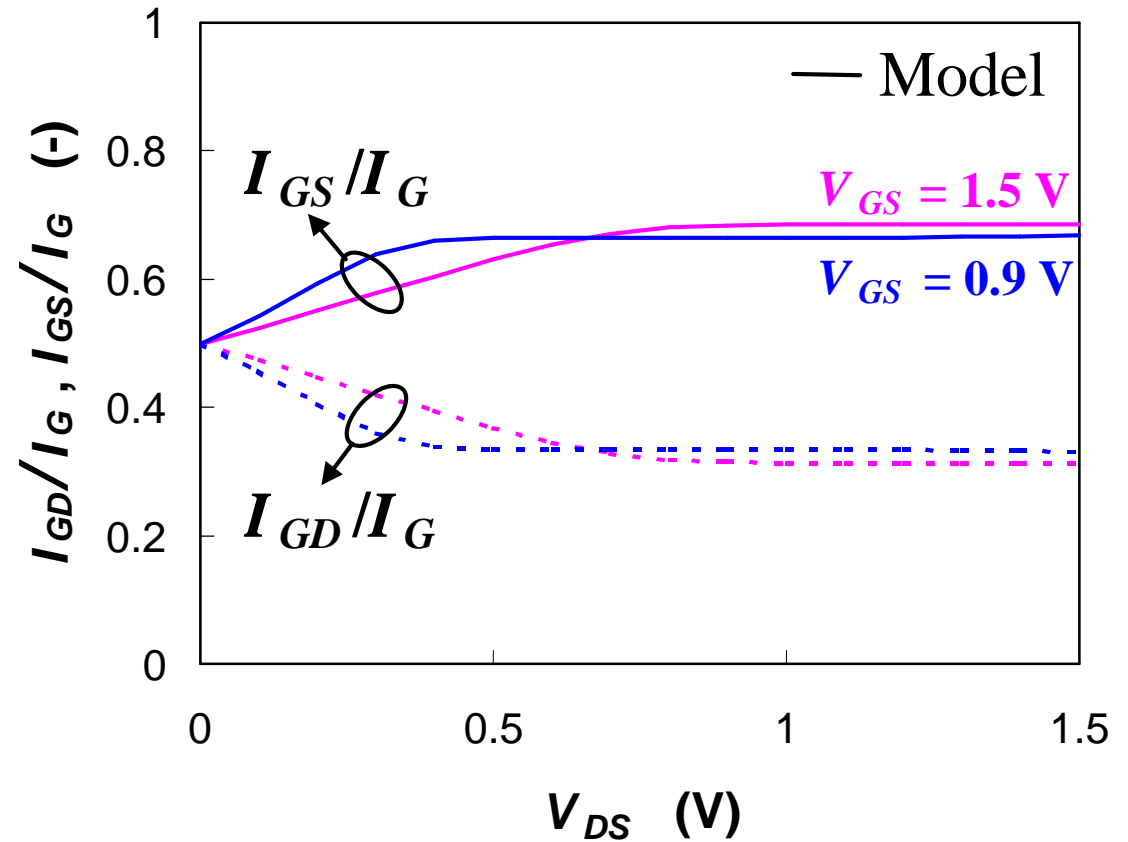
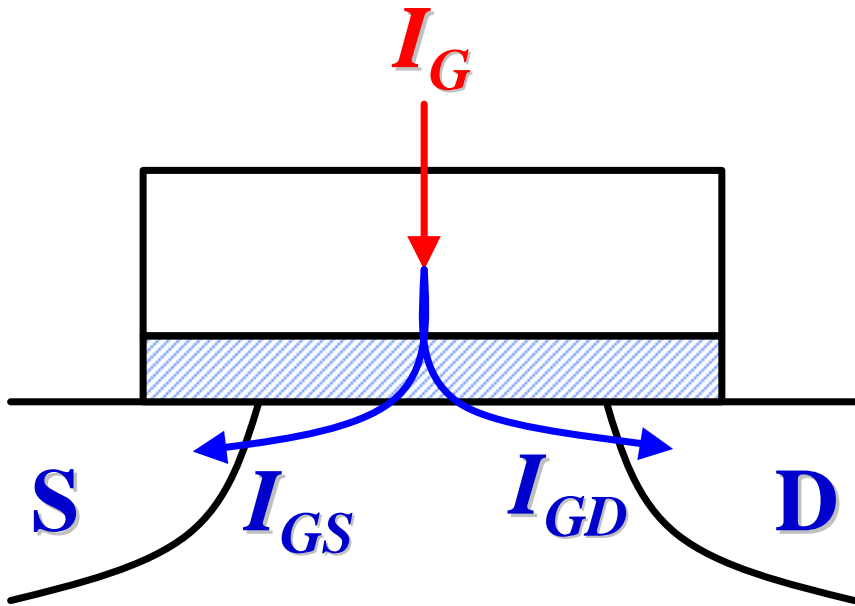
$$I_G = I_0 \cdot \int V_{ox} \cdot Q_{inv} \cdot e^{B_0 \cdot V_{ox}} \cdot dy / L$$



NMOS,  $V_{SB} = 0 \text{ V}$ ,  $t_{ox} = 2 \text{ nm}$ ,  $W/L = 10/0.6 \mu\text{m}$

# DC-Model : Gate Leakage Model (IV)

NMOS,  $t_{ox}=2$  nm,  $W/L=10/0.6\mu\text{m}$

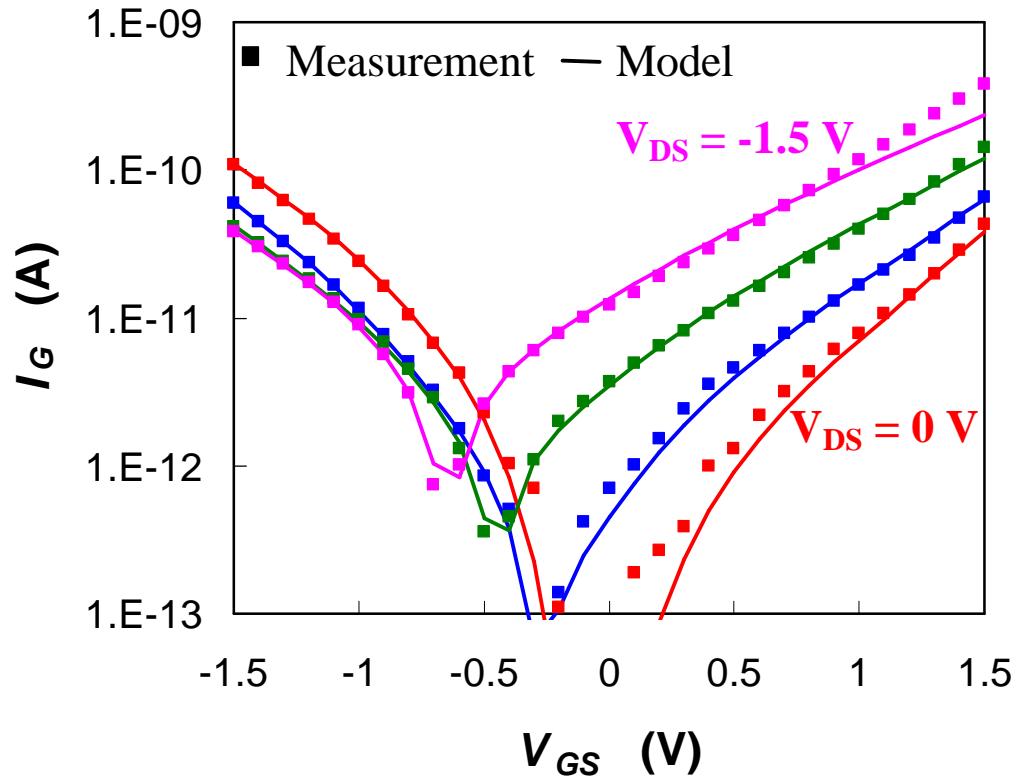


$$I_{GS} = I_G - I_{GD}$$

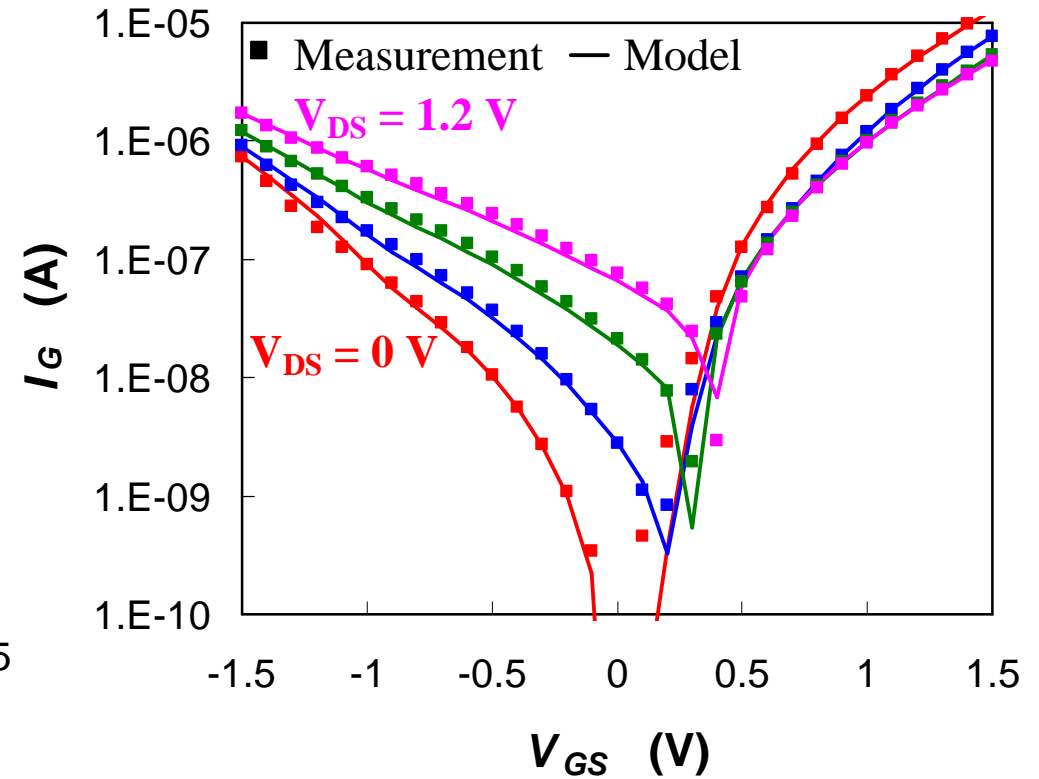
$$I_{GD} = I_0 \cdot \int_{y/L} \cdot V_{ox} \cdot Q_{inv} \cdot e^{B_0 \cdot V_{ox}} \cdot dy/L$$

# DC-Model : Gate Leakage Model (V)

$W/L=10/0.6\text{mm}$ ,  $V_{SB}=0\text{ V}$



**PMOS,  $t_{ox}=2\text{ nm}$**



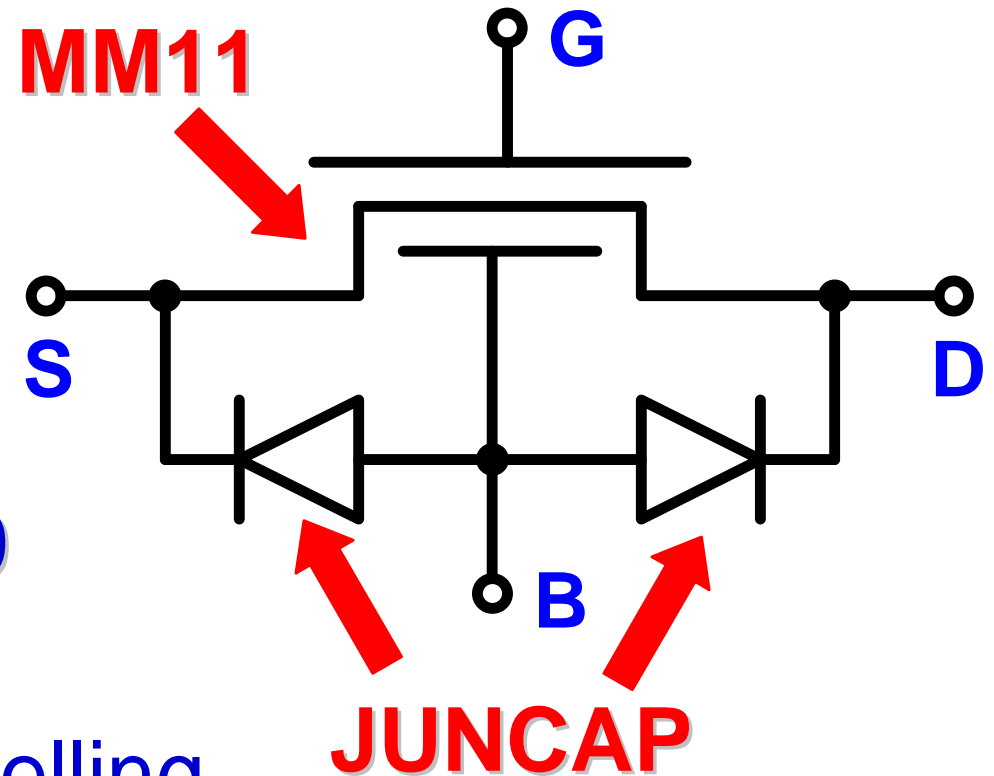
**NMOS,  $t_{ox}=1.55\text{ nm}$**

# DC-Model : Junction Model

Junctions modelled  
by JUNCAP-model

⇒ based on Level=500  
diode model:

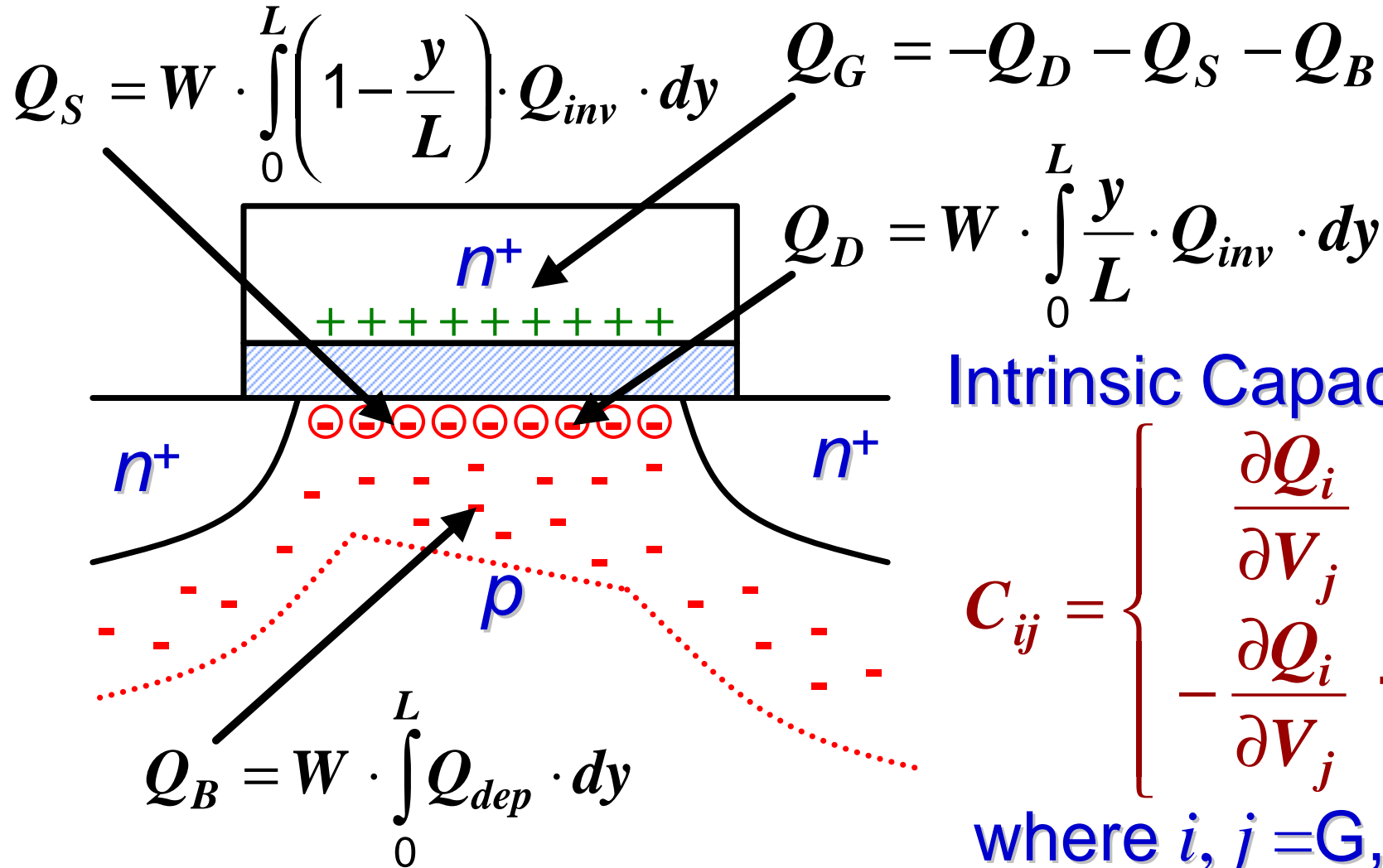
- trap-assisted tunnelling
- band-to-band tunnelling



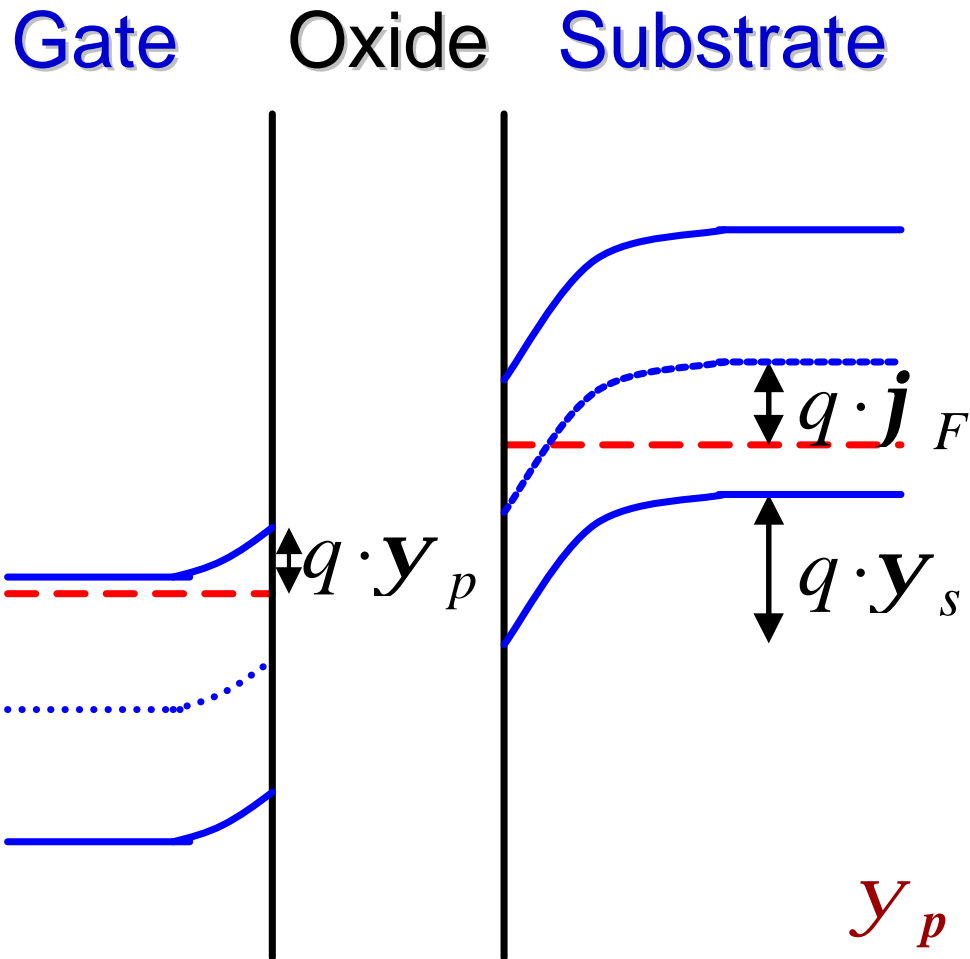
# Outline : AC-Model

- **Intrinsic charges**
- **Gate poly depletion**
- **Quantum-mechanical effects**
- **Bias-dependent overlap capacitance**

# AC-Model : Intrinsic Charges



# AC-Model : Gate Depletion Effect



Body factor of poly-silicon:

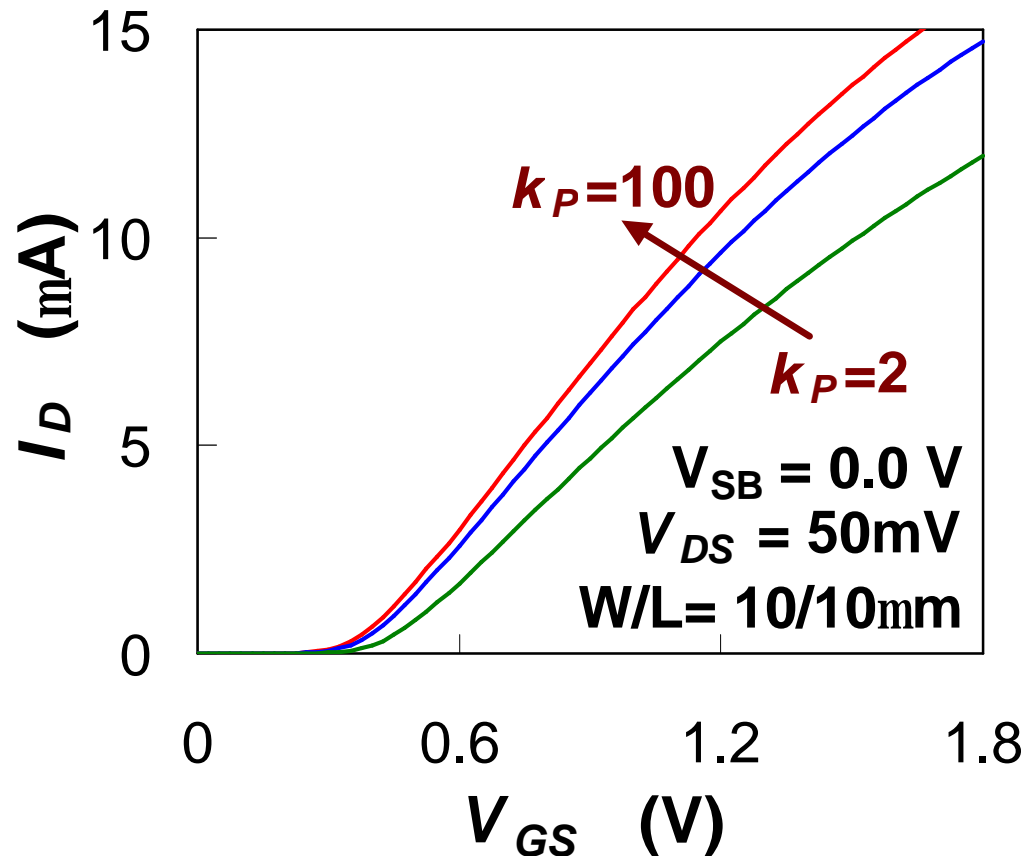
$$k_P = \frac{\sqrt{2 \cdot q \cdot e_{Si} \cdot N_P}}{C_{ox}}$$

Gate surface potential:

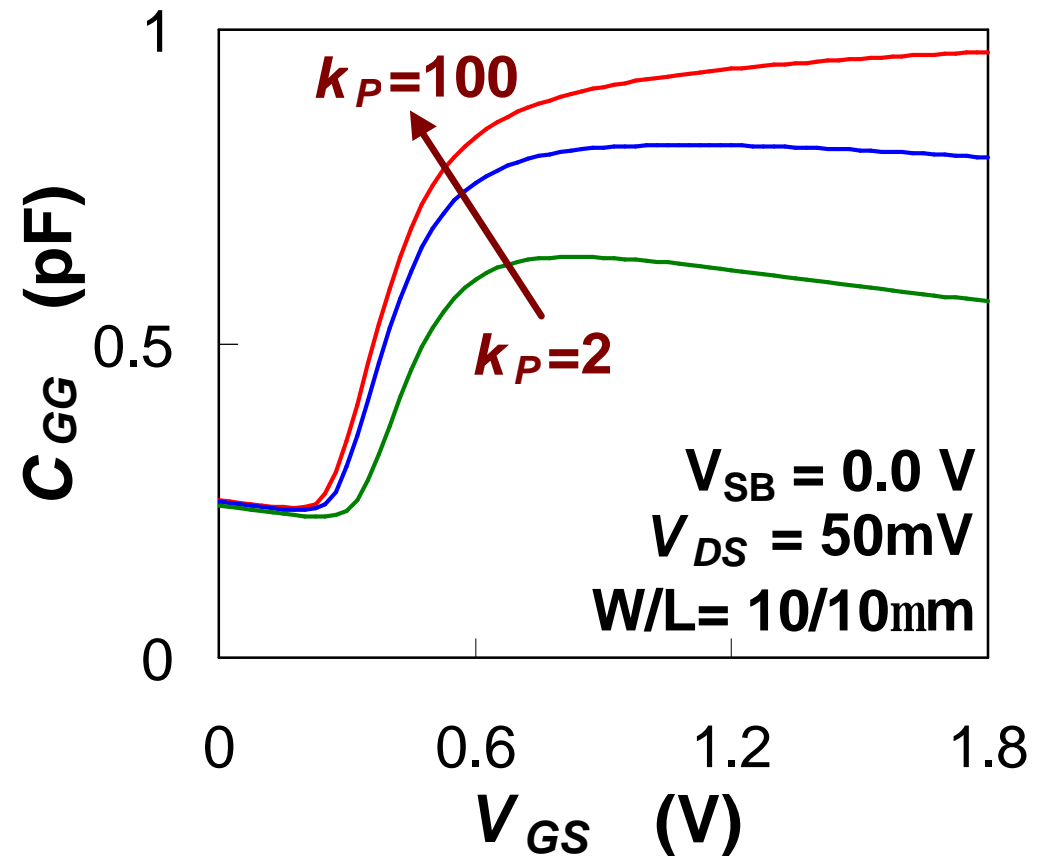
$$y_p = \frac{\alpha}{\epsilon} \sqrt{V_{GB} - V_{FB} - y_s + \frac{k_p^2}{4}} - \frac{k_p}{2} \frac{\ddot{0}^2}{\emptyset}$$

# AC-Model : Gate Depletion Effect (II)

## Drain current

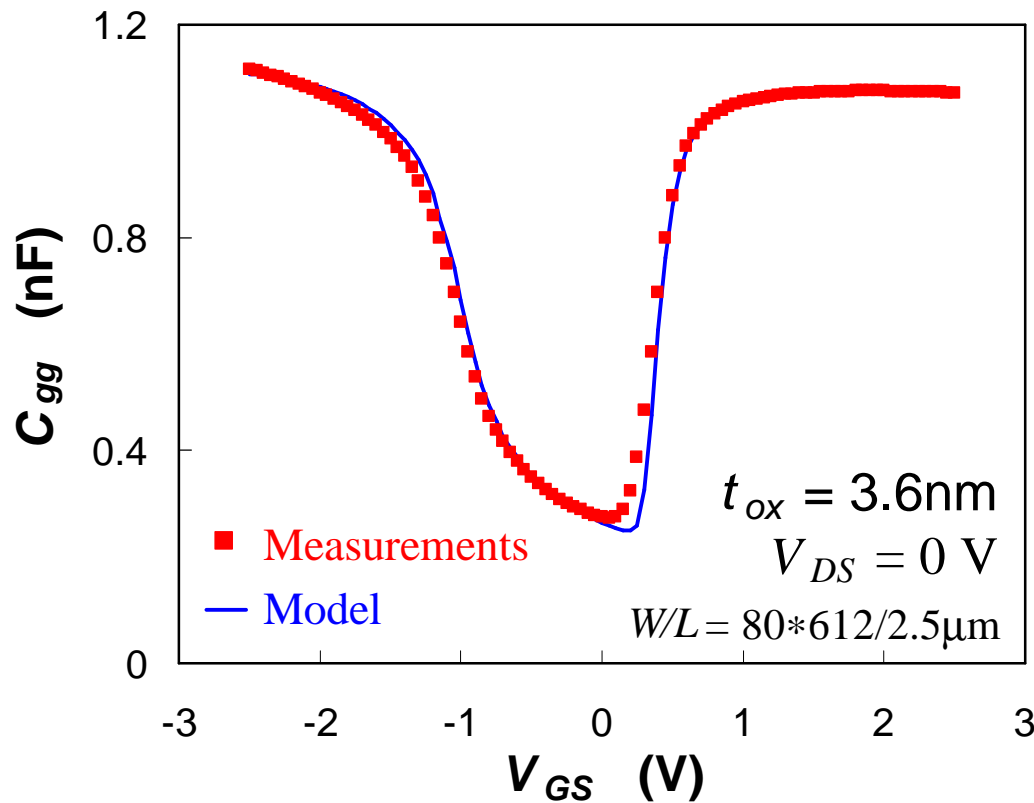


## Gate capacitance

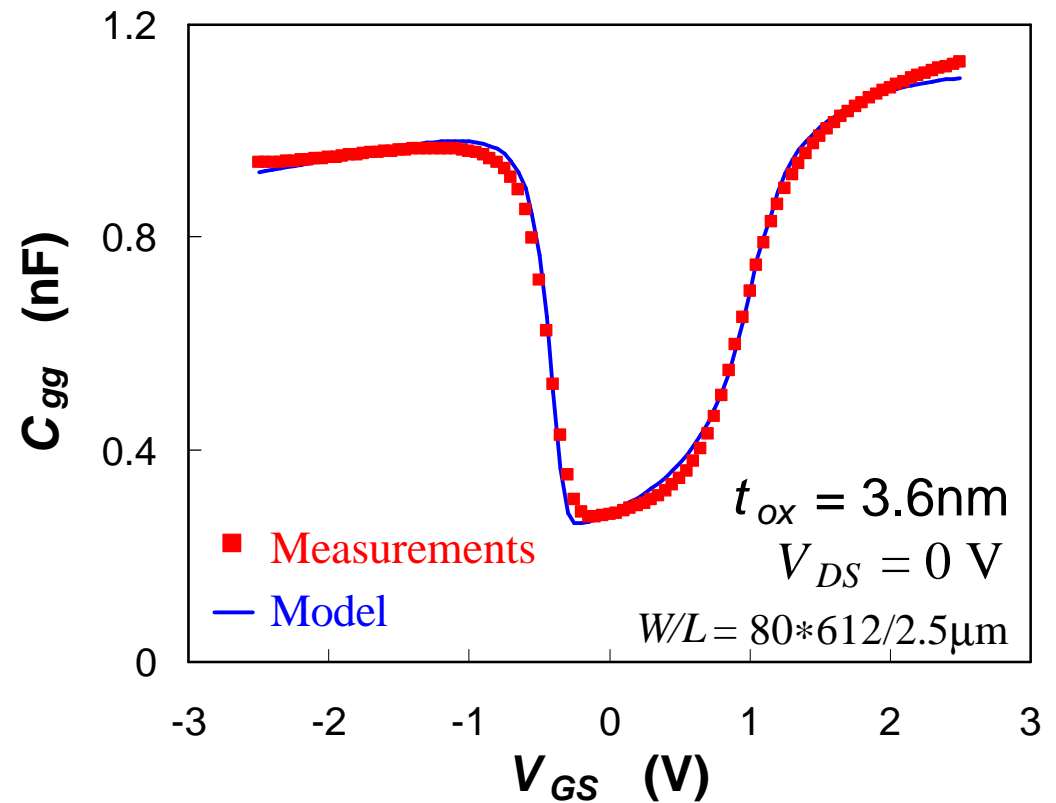


# AC-Model : Gate Depletion Effect (III)

Including gate depletion effect  $\Rightarrow$  using electrical  $t_{ox}$



NMOS

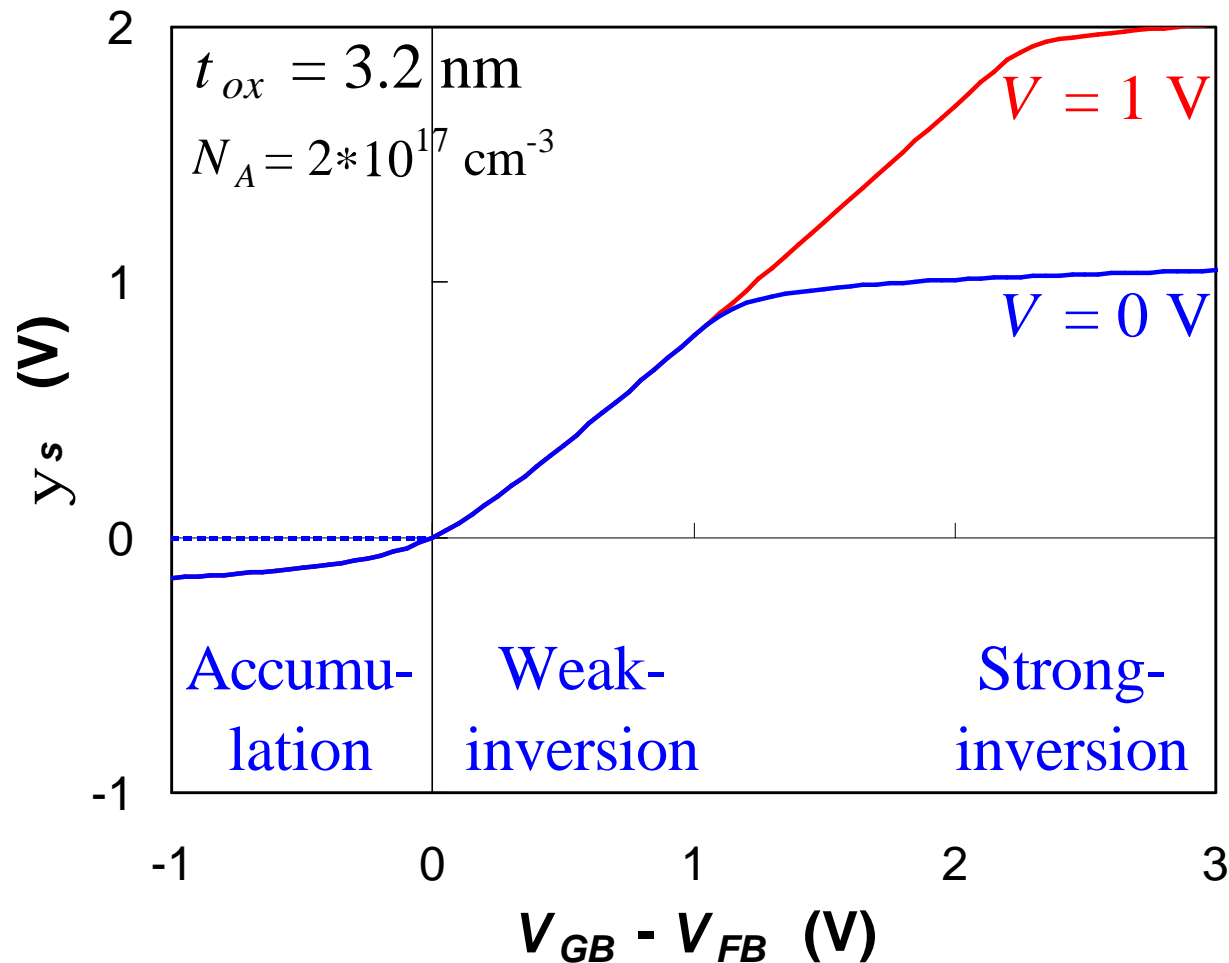


PMOS

0.18 $\mu\text{m}$   
CMOS

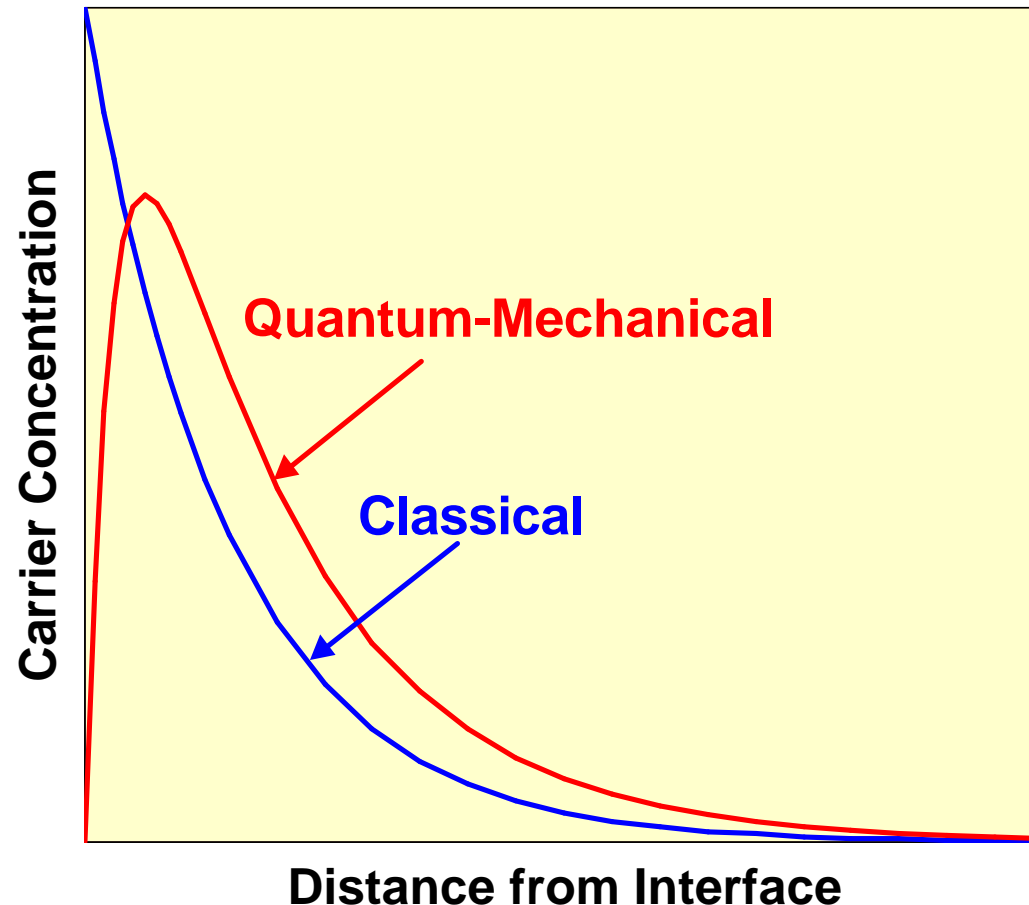
# AC-Model : Accumulation

Approximation in accumulation (no parameters added)



# AC-Model : Quantum-Mechanical Effects

Inversion-layer is formed at distance  $\Delta z$  from interface



$$\Delta z \propto E_{eff}^{-1/3}$$

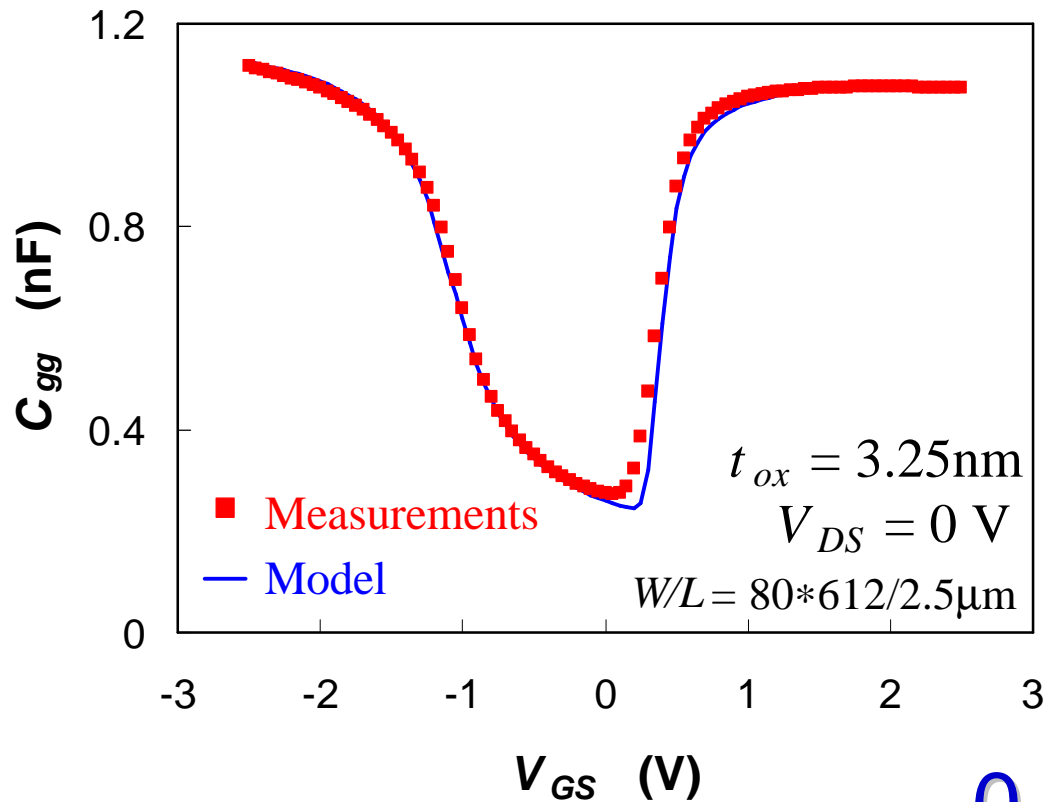
(F. Stern, CRC Crit. Rev. Solid State Sci., pp.499-514, 1974)

Effective oxide thickness:

$$t_{ox_{eff}} = t_{ox} + \frac{e_{ox}}{e_{Si}} \cdot \Delta z$$

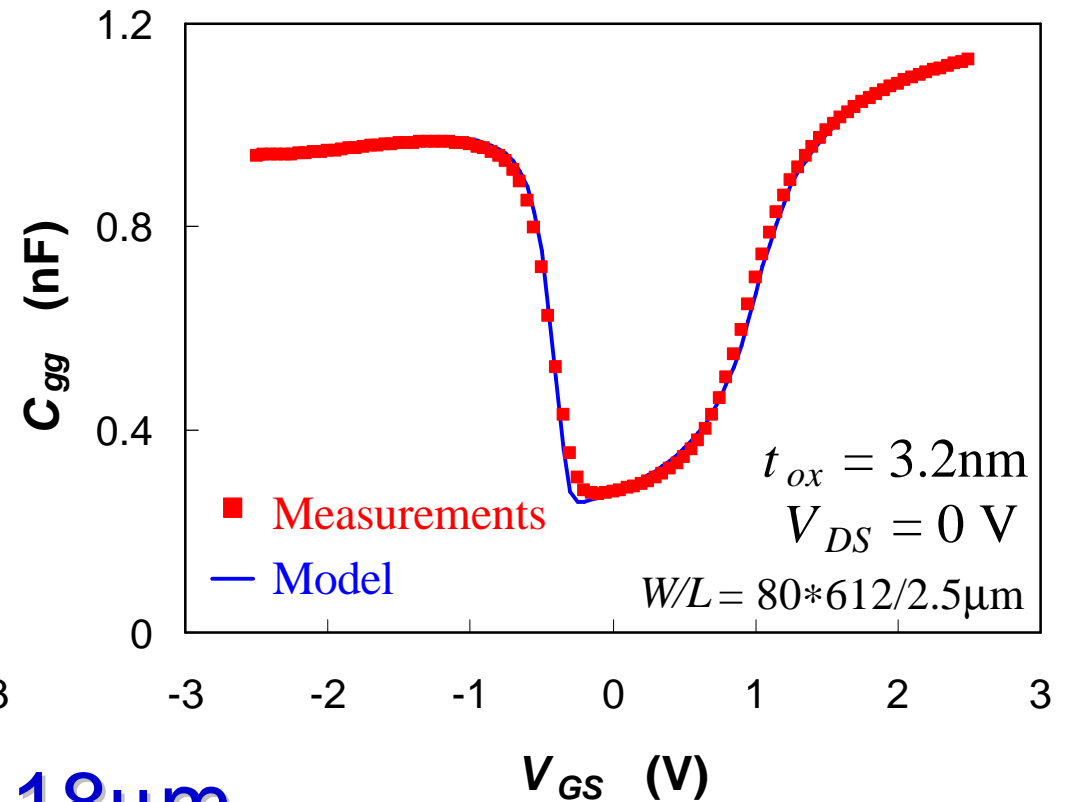
# AC-Model : QM-Effects (II)

Including QM-effects  $\Rightarrow$  using physical  $t_{ox}$



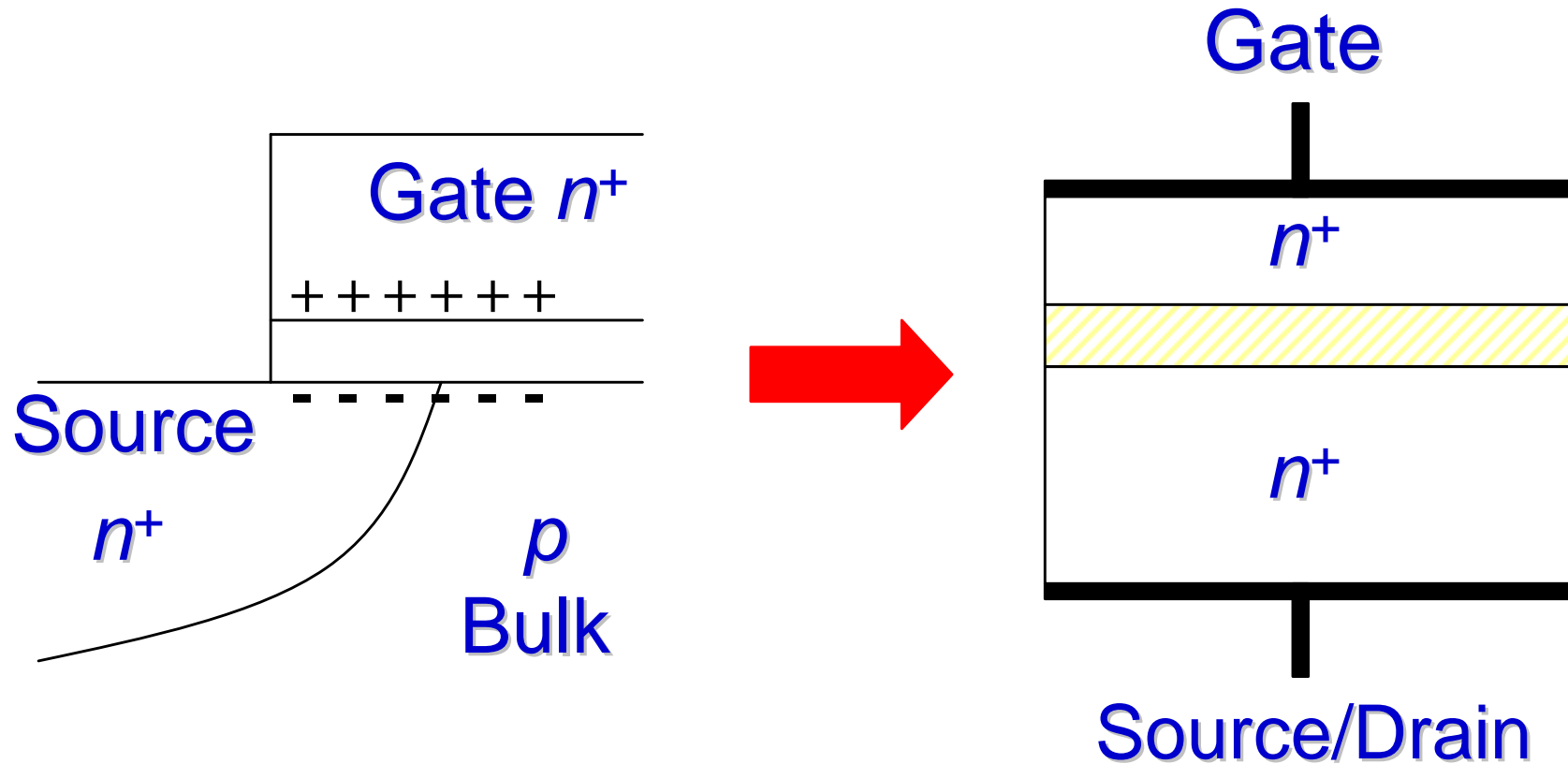
NMOS

0.18  $\mu\text{m}$   
CMOS



PMOS

# AC-Model : Bias-Dependent Overlap Capacitance

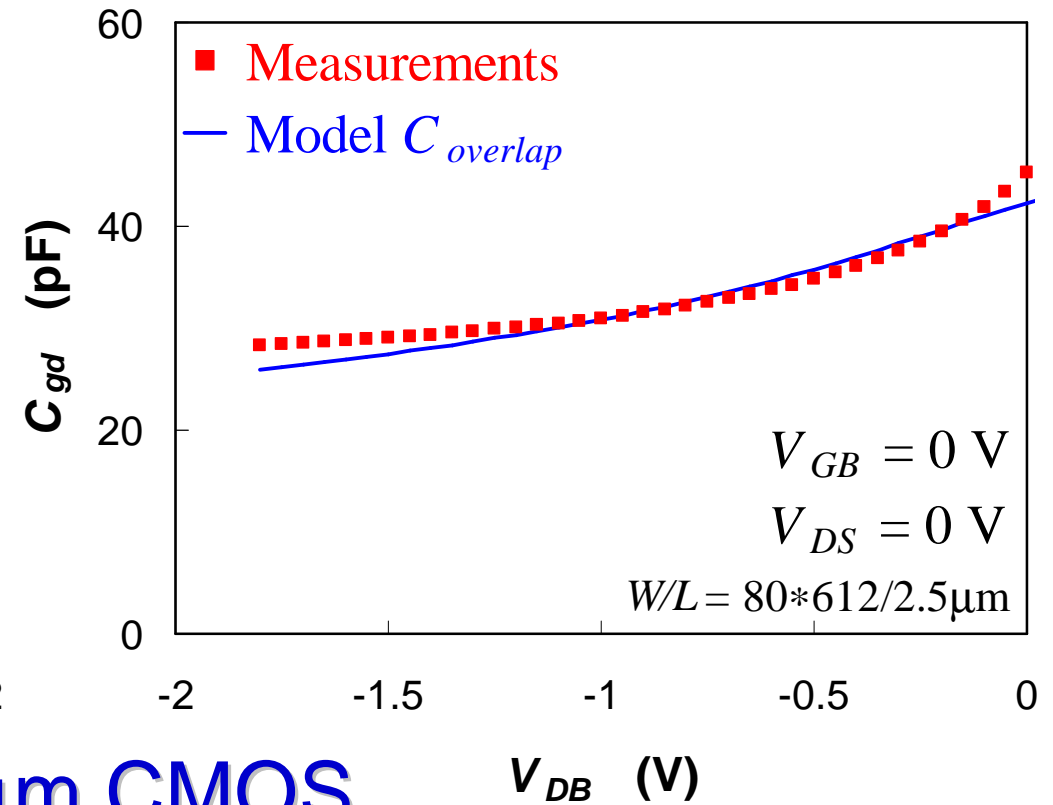
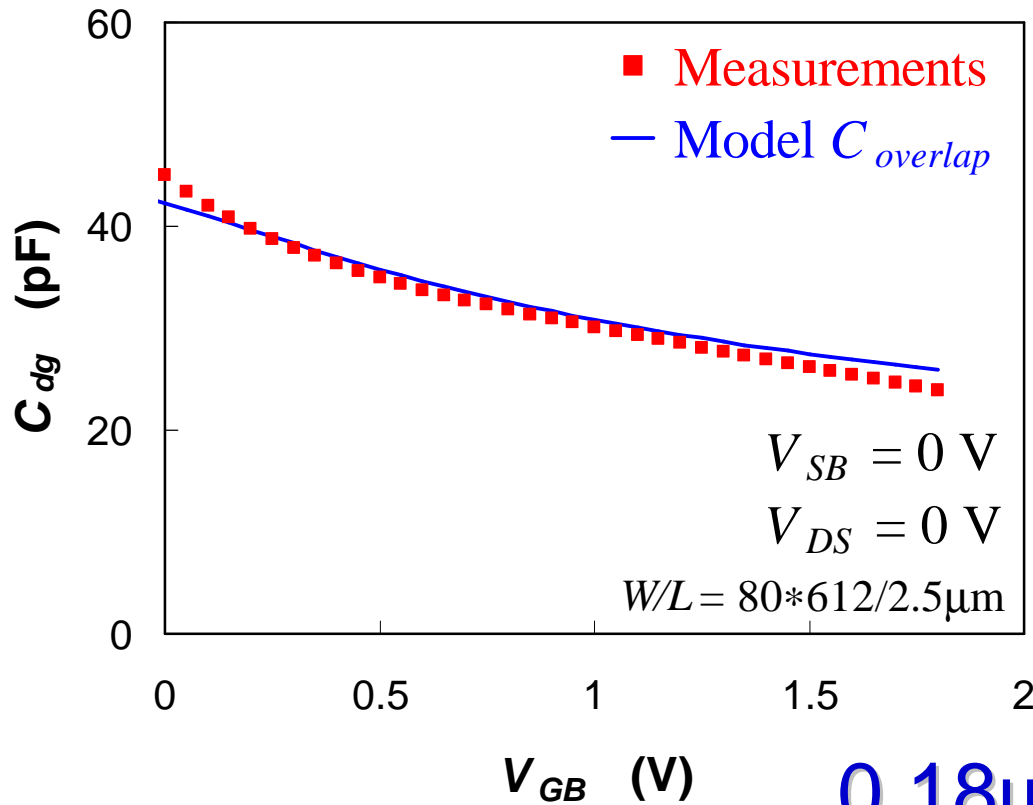


Two-terminal MOS-capacitance

Accumulation and depletion region included

# AC-Model : Bias-Dependent Overlap Capacitance (II)

Two parameters ( $V_{FBov}$  and  $k_{ov}$ )



$C_{DG}$

0.18  $\mu\text{m}$  CMOS  
PMOS

$C_{GD}$

# Outline

- Introduction
- DC-Model
- AC-Model
- **Noise Model**
- Model Parameters & Extraction
- Examples & Applications
- Conclusions

# Noise Model

- **1/f-Noise: Unified Model (BSIM4, MM9)**

(Kwok K. Hung et al., IEEE TED-37 (3), p.654 , 1990;  
 ibid. (5), p.1323, 1990)

- **Thermal Noise:**

$$S_{ID} = \frac{4 \times k_B \times T}{I_D \times L^2} \times \int_0^{VD(SAT)} g^2(V) \times dV \quad \text{where: } g(V) = -W \times \mu(V) \times Q_{inv}(V)$$

(F.M. Klaassen & J. Prins , Philips Res. Repts. 22, pp.504-514, 1967)

MOS Model 9

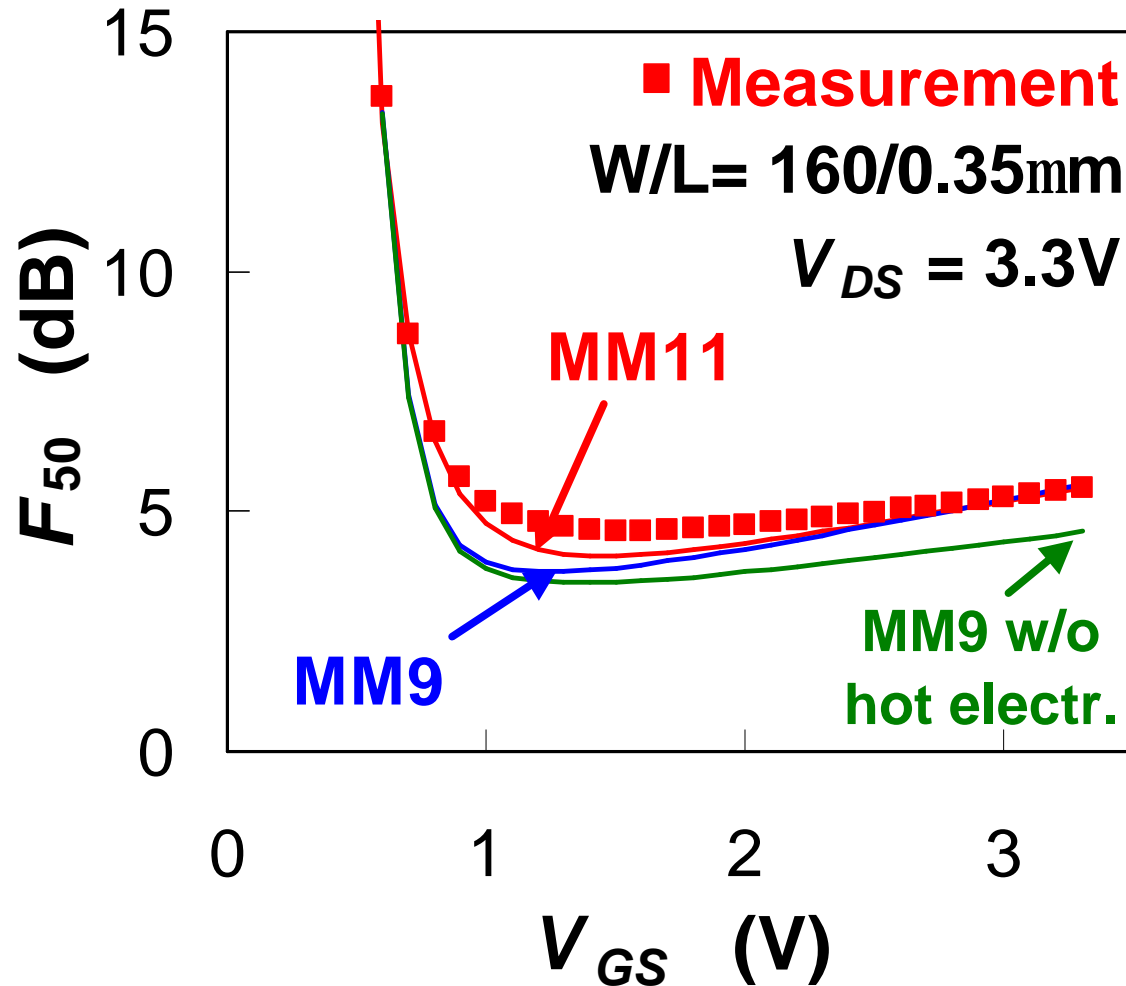
$$m = \frac{m_{eff}}{1 + \frac{m_{eff}}{v_{sat}} \times E_{||}}$$

MOS Model 11

$$m = \frac{m_{eff}}{\sqrt{1 + \frac{\alpha m_{eff}}{\xi e} \frac{1}{v_{sat}} \times E_{||}^2}}$$

# Noise Model : Thermal Noise

## 50W Noise Figure

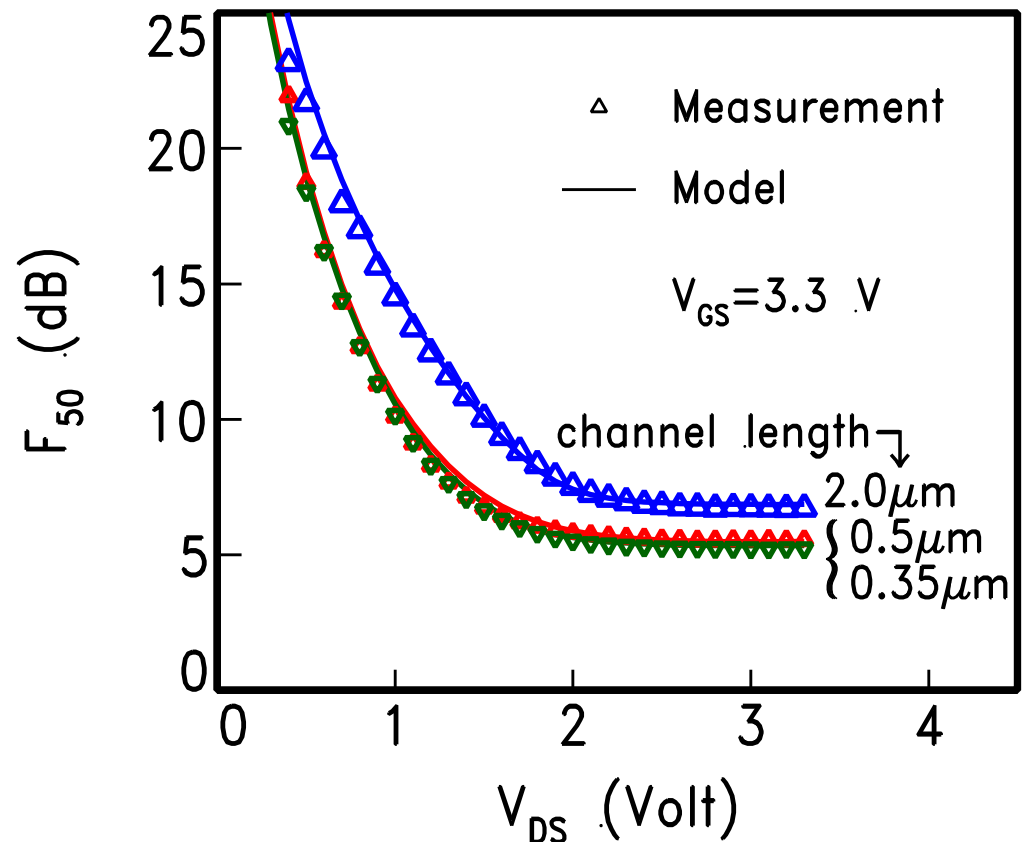
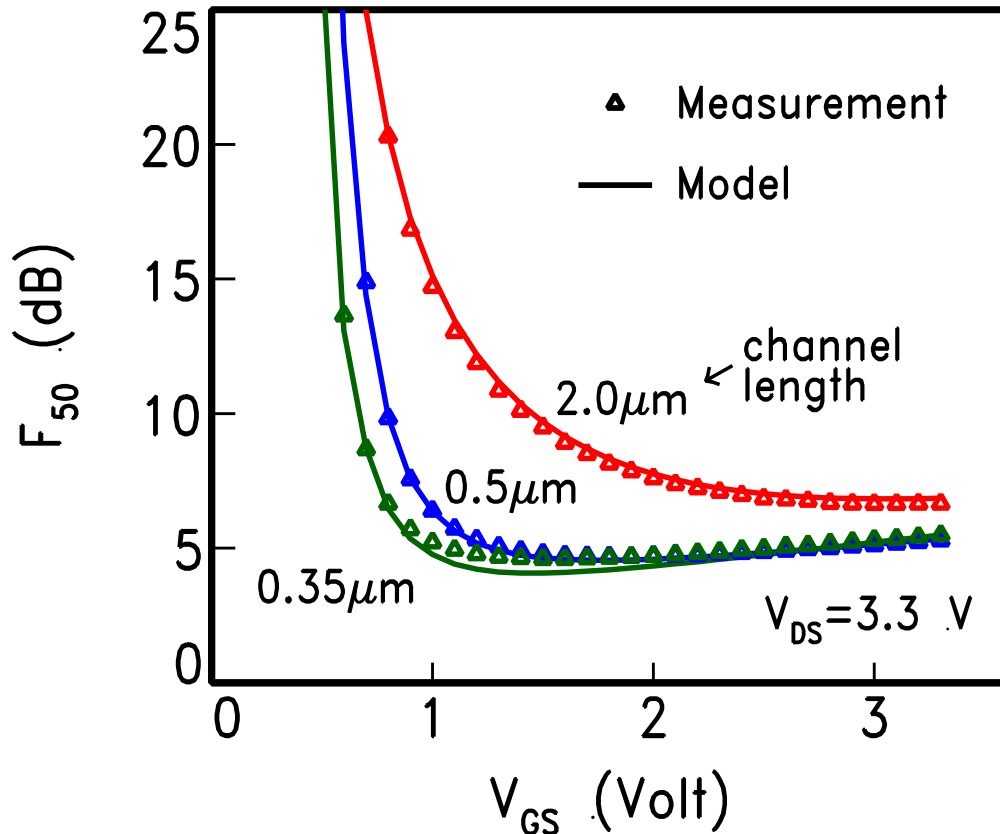


⇒ no hot electron effect needed to describe noise behaviour

(A.J. Scholten et al., IEDM Tech. Dig., pp.155-158, 1999)

# Noise Model : Thermal Noise (II)

## 50W Noise Figure (no noise parameters needed)

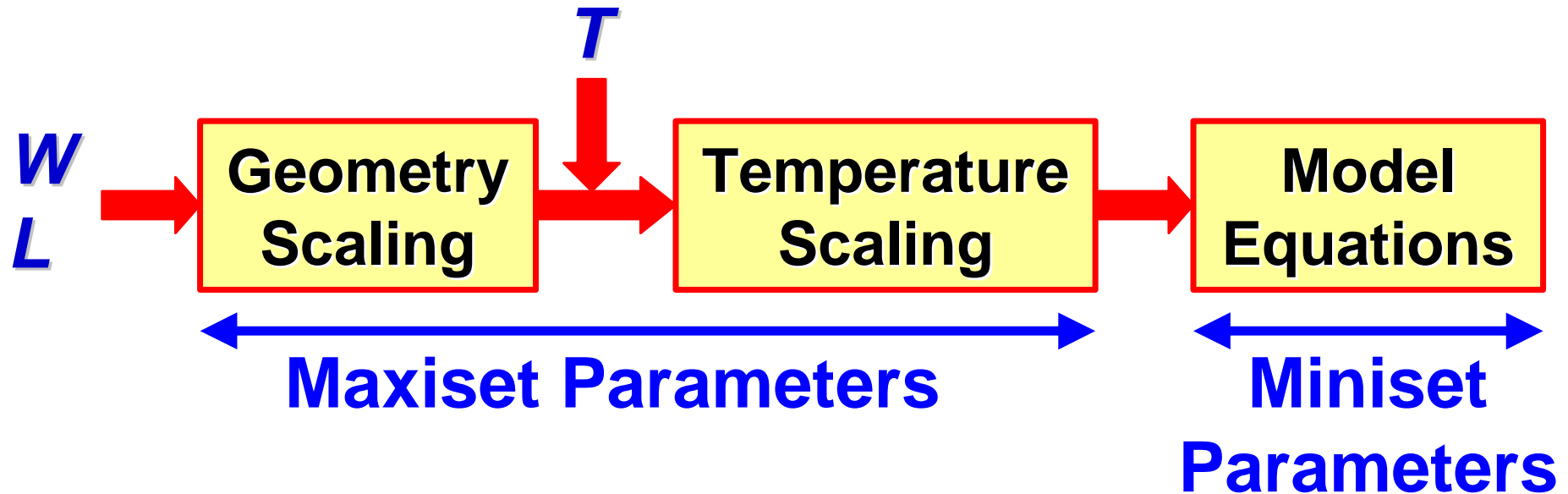


**Verified on 0.35 $\mu\text{m}$ , 0.25 $\mu\text{m}$  and 0.18 $\mu\text{m}$  CMOS**  
(A.J. Scholten et al., IEDM Tech. Dig., pp.155-158, 1999)

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# Model Parameters & Extraction



$$k_R + s_L \times \left( \frac{1}{L} - \frac{1}{L_R} \right) + s_{L^2} \times \left( \frac{1}{L^2} - \frac{1}{L_R^2} \right) + s_W \times \left( \frac{1}{W} - \frac{1}{W_R} \right) = k$$

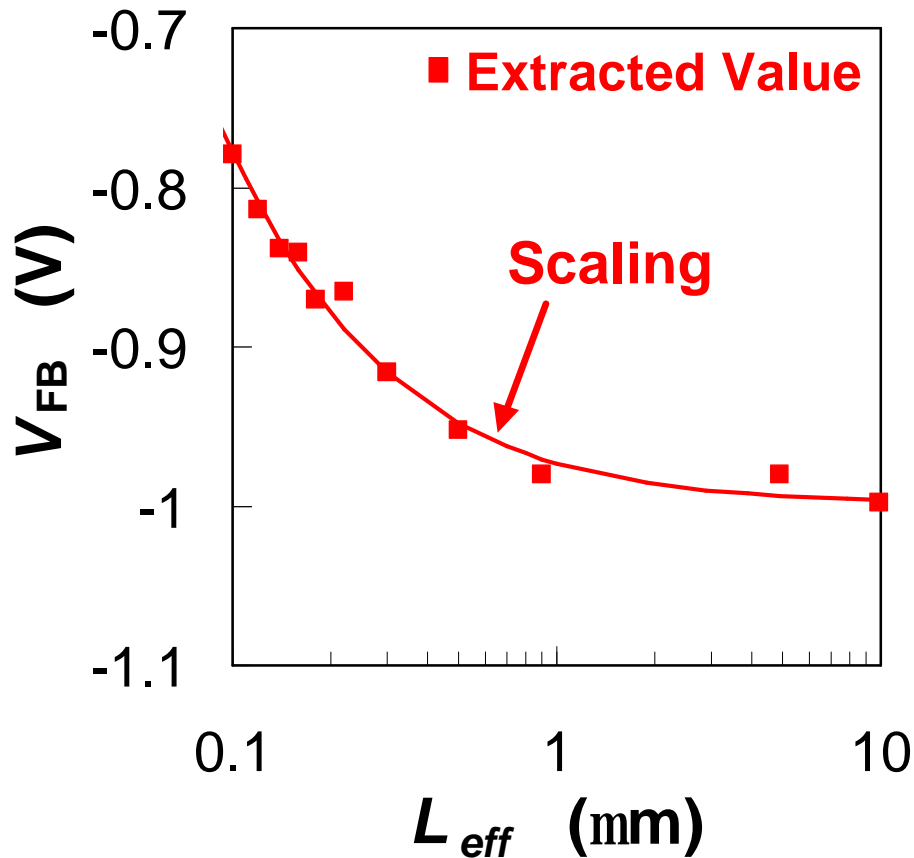
# Model Parameters & Extraction (II)

Description of:	Parameters:
Single device	40
<i>T</i> -scaling	11
Geometry scaling	39
Complete technology	90 +

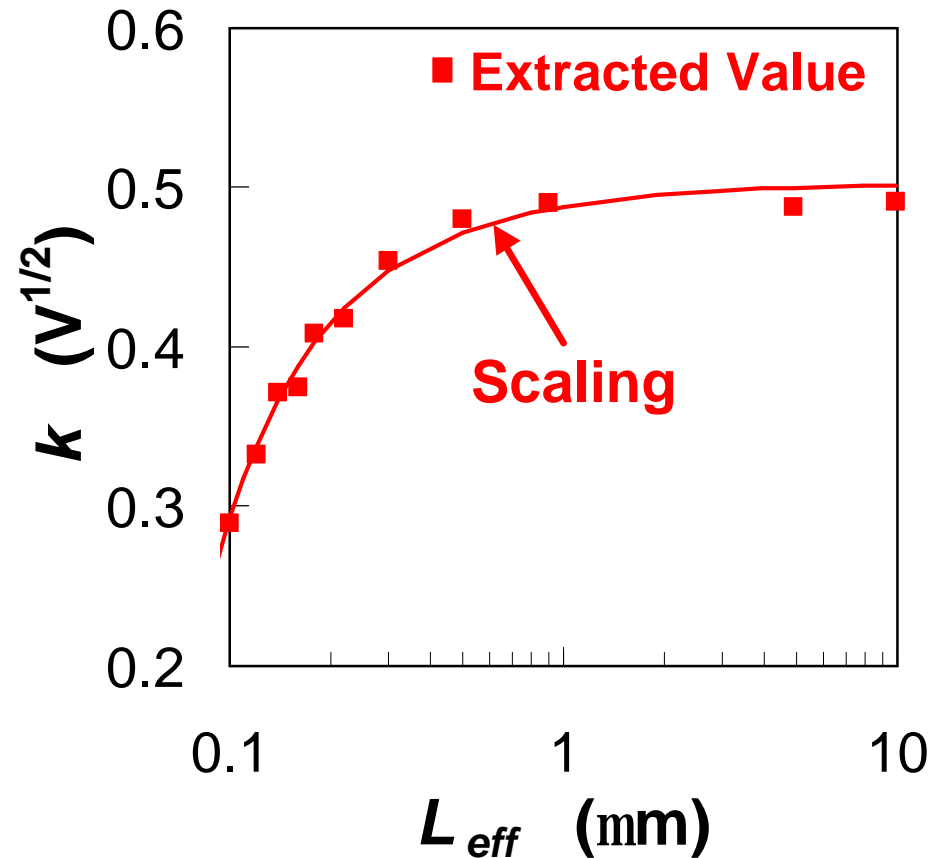
⇒ Binning will also be an option

# Model Parameters : Parameter Scaling

Different parameters have different scaling relations



Flat-band voltage



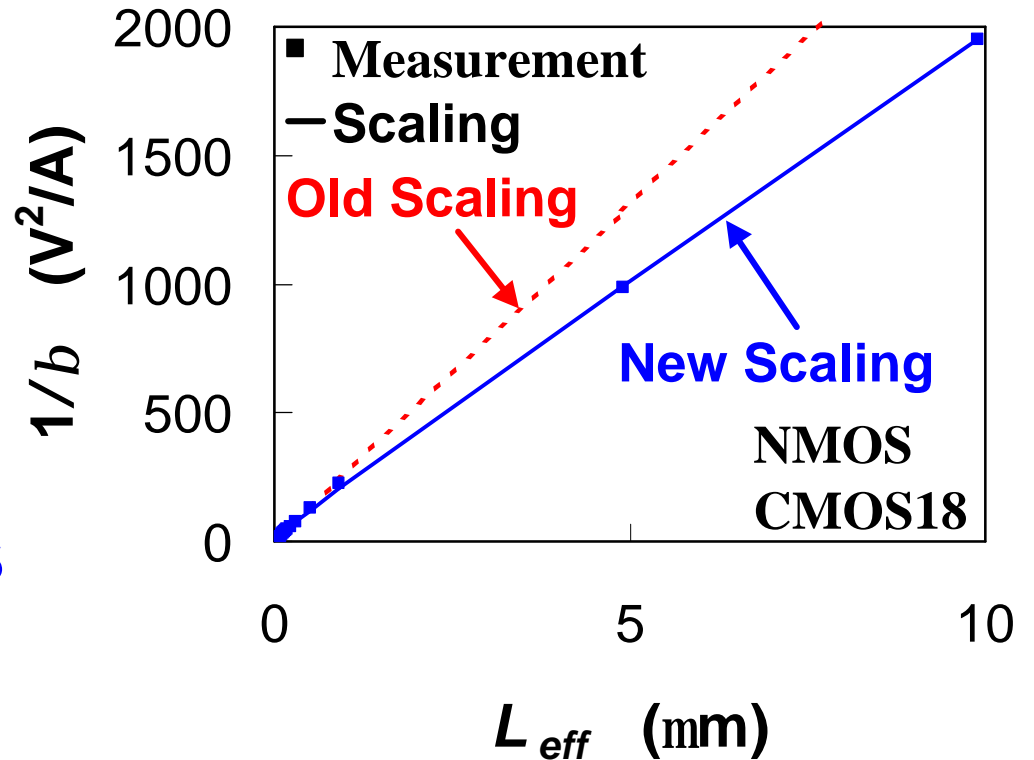
Body factor

# Model Parameters : Parameter Scaling (II)

- Old  $\beta$ -scaling:

$$b = b_{sq} \times \frac{W_{eff}}{L_{eff}}$$

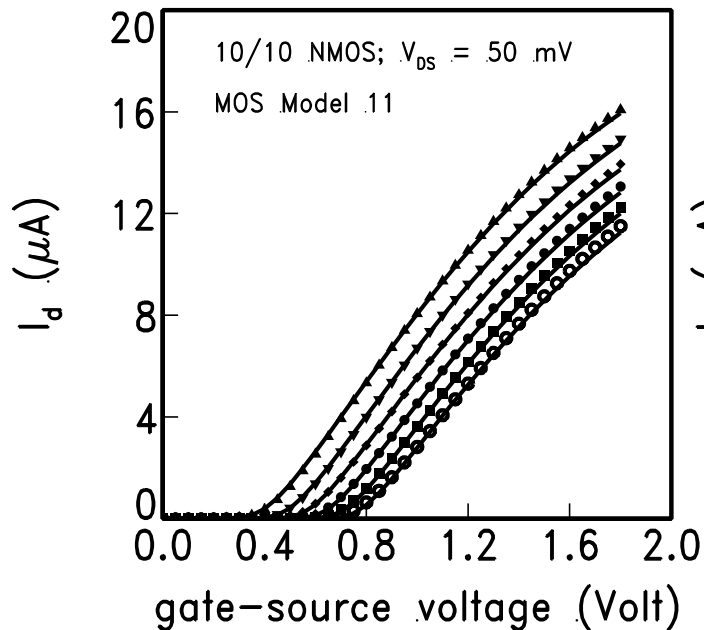
➤ influence of pockets



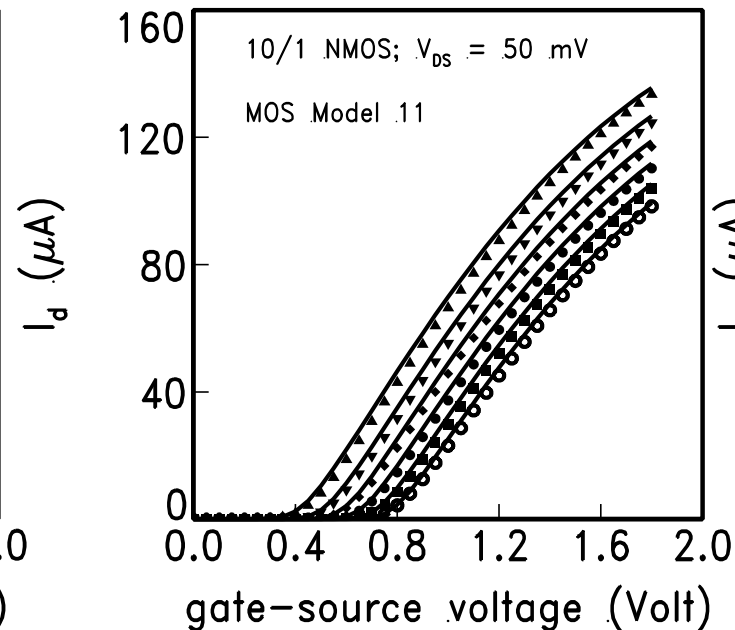
- New  $\beta$ -scaling: 
$$b = \frac{b_{sq}}{1 + \frac{b_{sq}}{Db} \times \frac{L_p}{L_{eff}} \times \frac{1 - \exp\left(-\frac{L_{eff}}{L_p}\right)}{L_p}} \times \frac{W_{eff}}{L_{eff}}$$

# Model Parameters : Scaling for 0.18 $\mu\text{m}$ CMOS

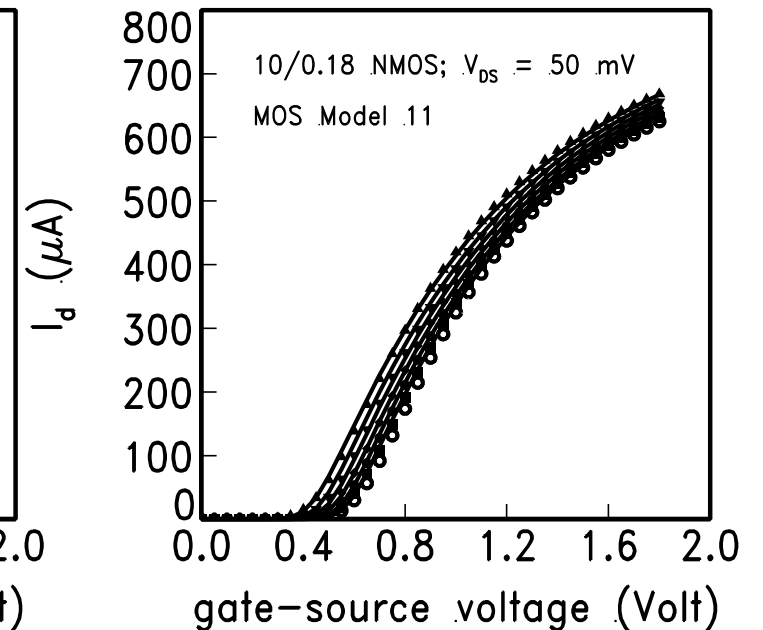
## $I_D - V_{GS}$ -characteristics



$L=10\mu\text{m}$



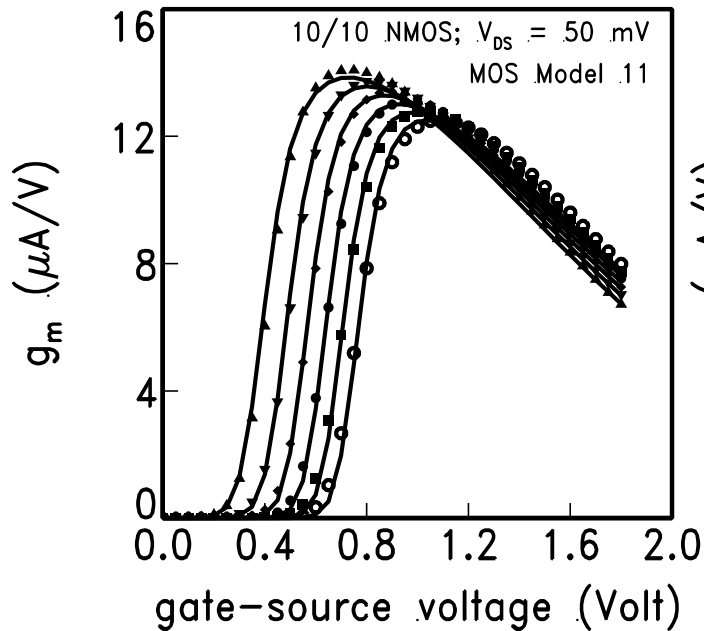
$L=1\mu\text{m}$



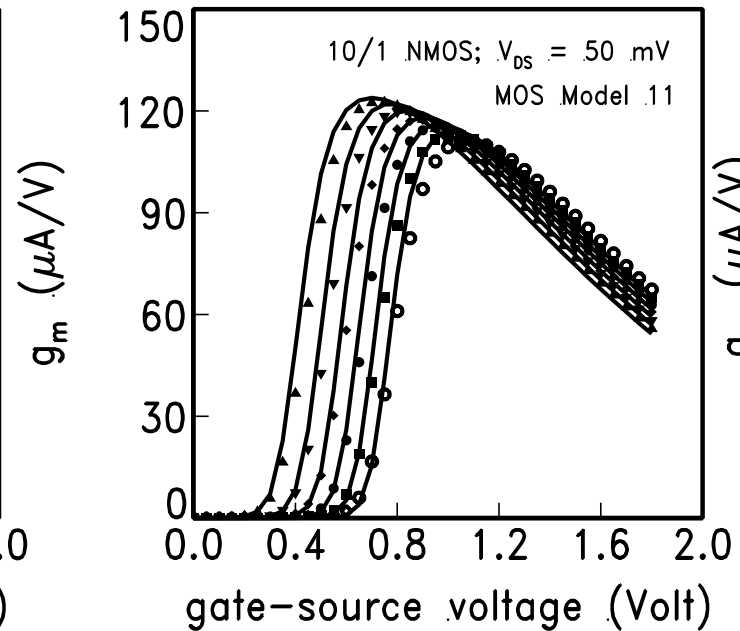
$L=0.18\mu\text{m}$

# Model Parameters : Scaling for 0.18 $\mu\text{m}$ CMOS (II)

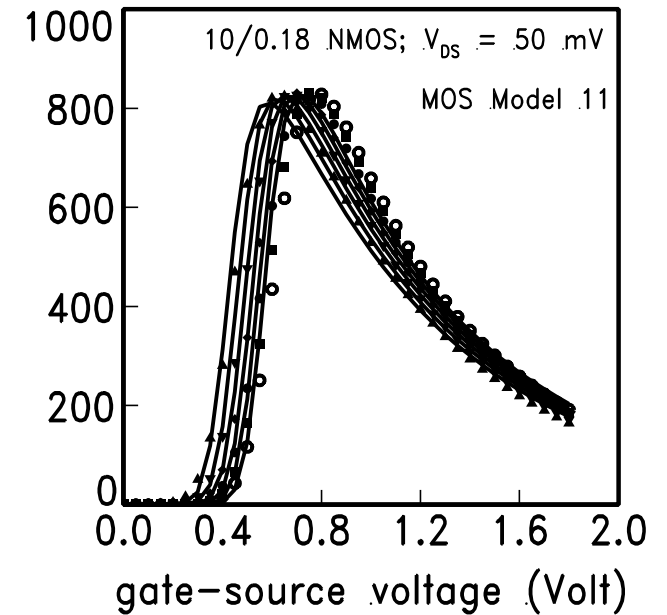
## $g_m - V_{GS}$ -characteristics



$L=10\mu\text{m}$



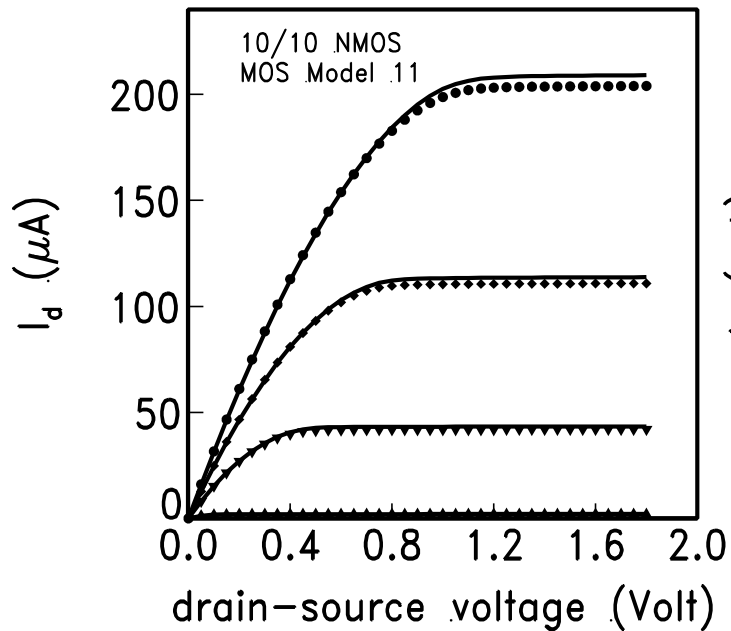
$L=1\mu\text{m}$



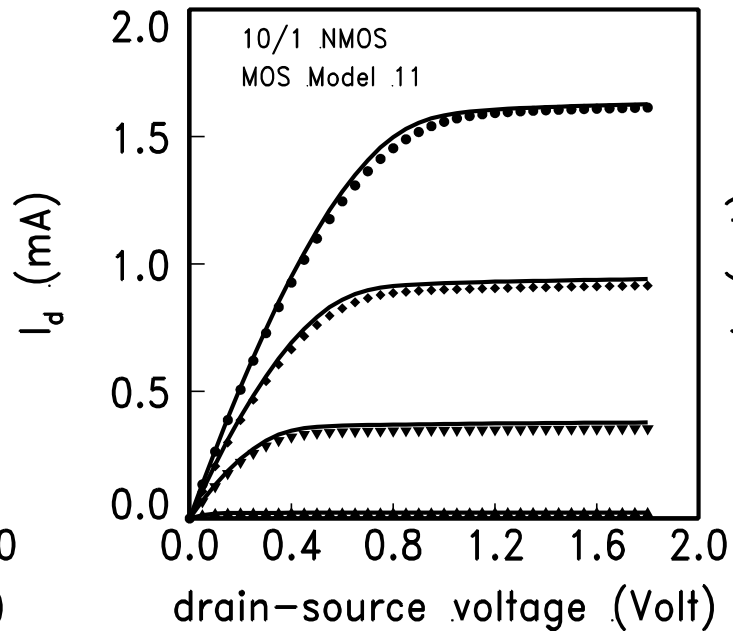
$L=0.18\mu\text{m}$

# Model Parameters : Scaling for 0.18 $\mu\text{m}$ CMOS (III)

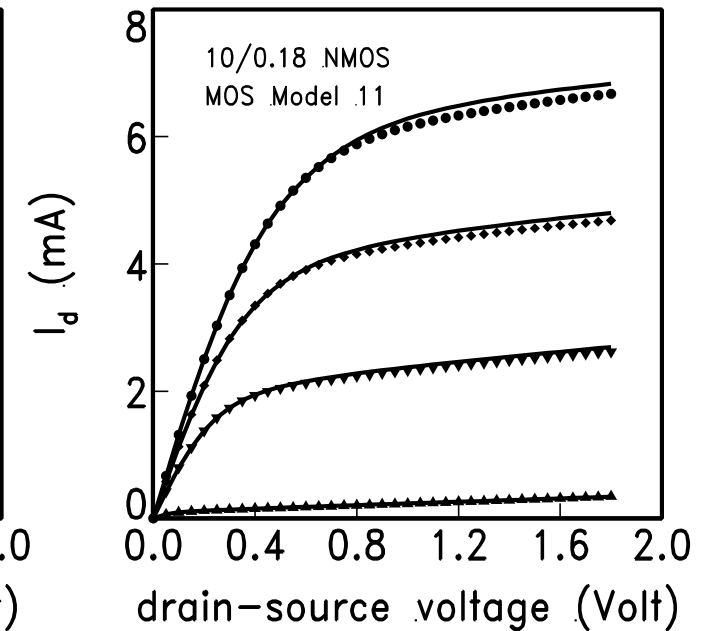
## $I_D - V_{DS}$ -characteristics



$L=10\mu\text{m}$



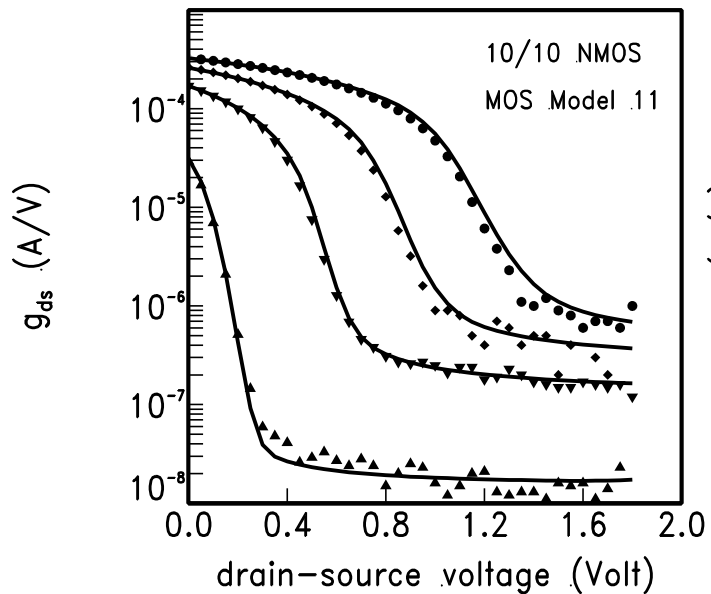
$L=1\mu\text{m}$



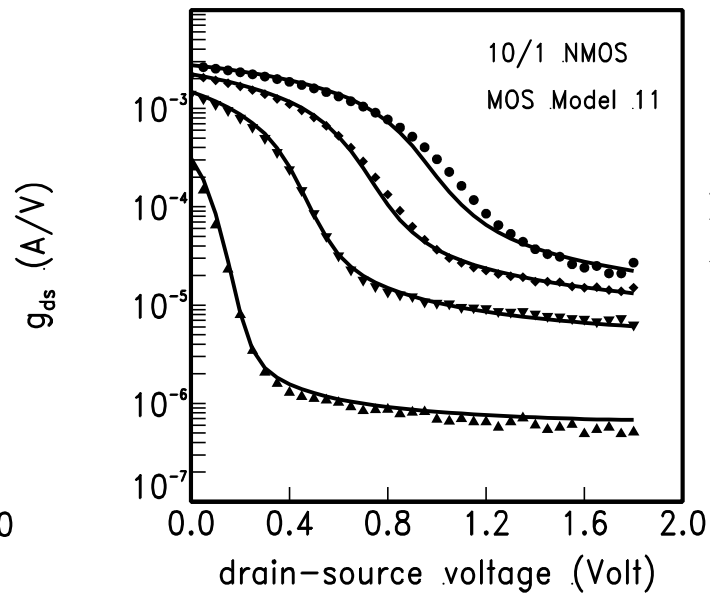
$L=0.18\mu\text{m}$

# Model Parameters : Scaling for 0.18mm CMOS (IV)

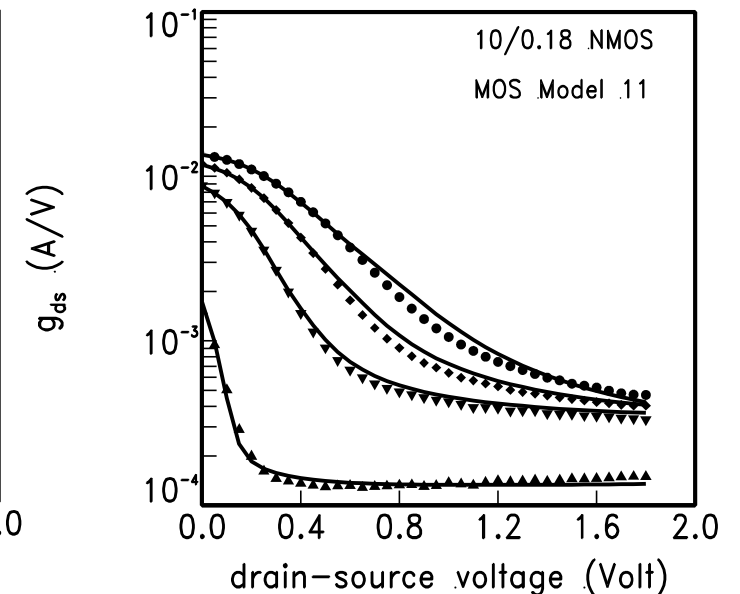
## $g_{ds} - V_{DS}$ -characteristics



$L=10\mu\text{m}$



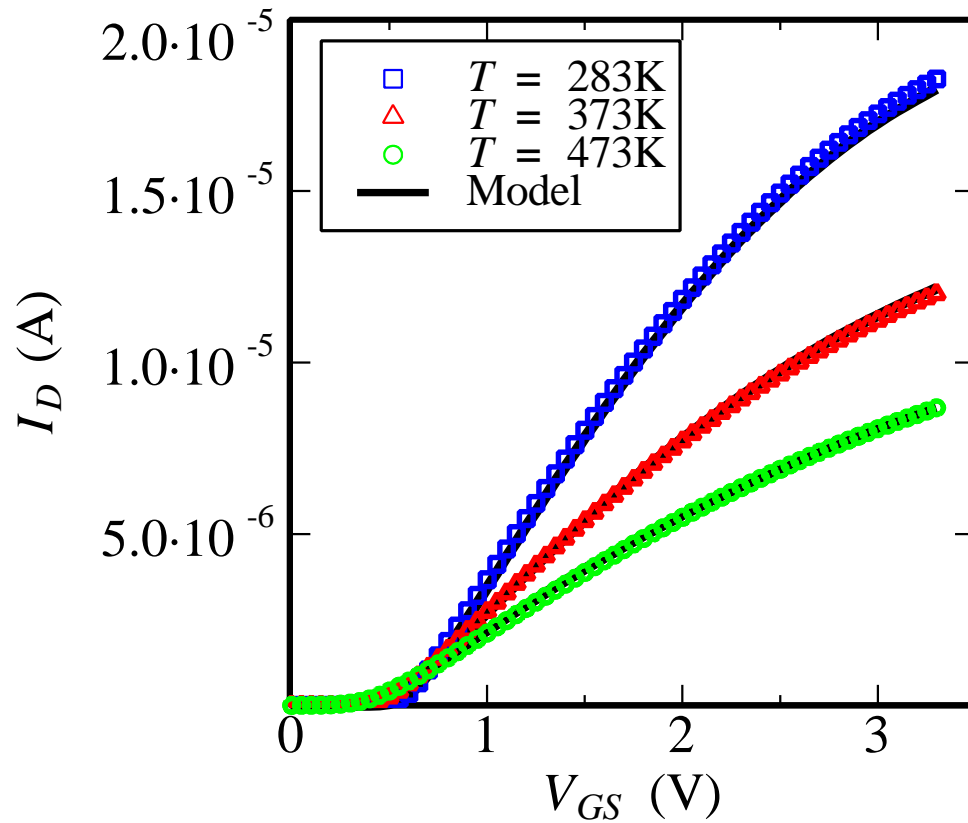
$L=1\mu\text{m}$



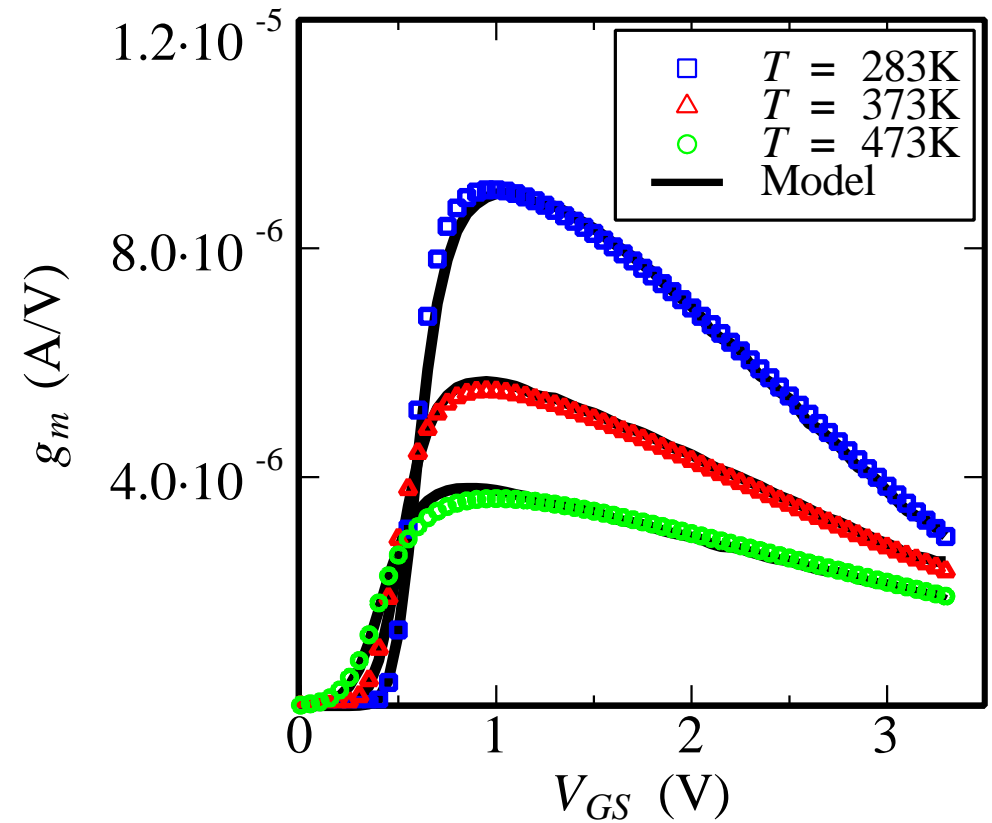
$L=0.18\mu\text{m}$

# Model Parameters : Temperature Scaling

NMOS,  $W/L=10/10\mu\text{m}$ ,  $V_{SB}=0\text{ V}$



$I_D - V_{GS}$



$g_m - V_{GS}$

# Model Parameters : Parameter Extraction

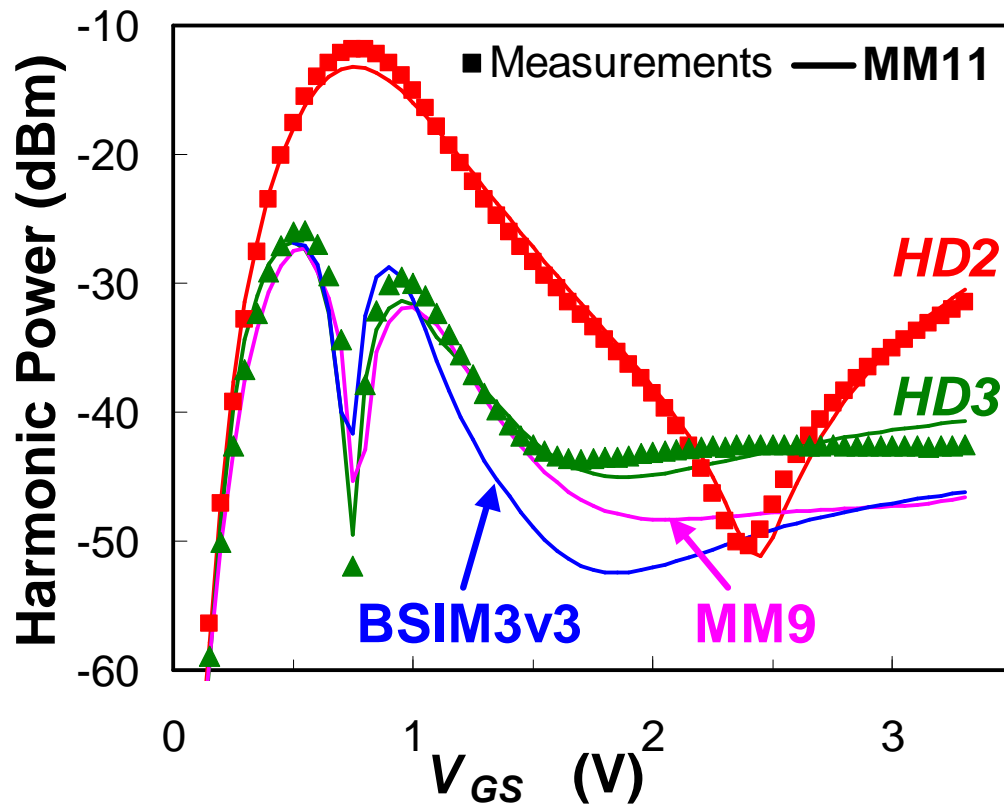
Characteristics:	Parameters:	Fitted on:
Subthreshold	Subthreshold	$I_D$
Gate Capacitance	Poly depletion	$C_{gg}$
Linear Region	Mobility, $R_{series}$	$I_D$ & $g_m$
Output	Velocity saturation	$I_D$
	Conductance	$g_d$
Substrate Current	Weak-avalanche	$I_B$
Gate Current	Gate leakage	$I_G$

# Outline

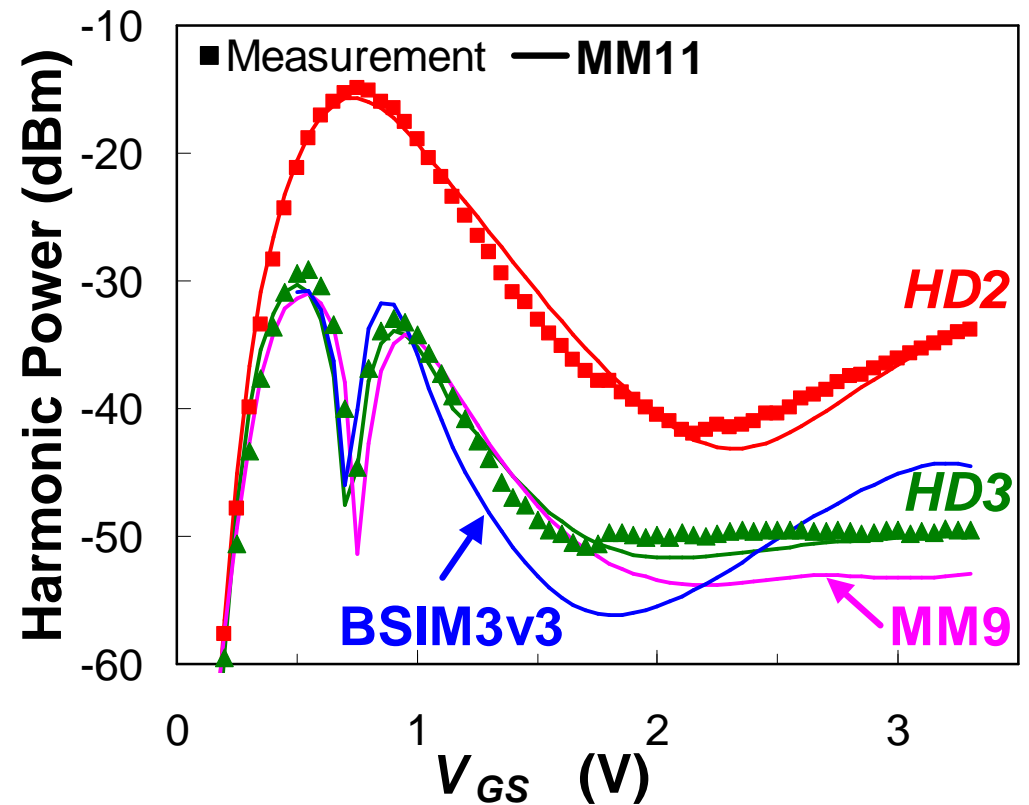
- **Introduction**
- **DC-Model**
- **AC-Model**
- **Noise Model**
- **Model Parameters & Extraction**
- **Examples & Applications**
- **Conclusions**

# Examples & Applications : RF-Distortion

NMOS,  $W/L=160/0.35\mu\text{m}$ ,  $V_{DS}=3.3\text{ V}$ ,  $P_{IN}=-5\text{dBm}$



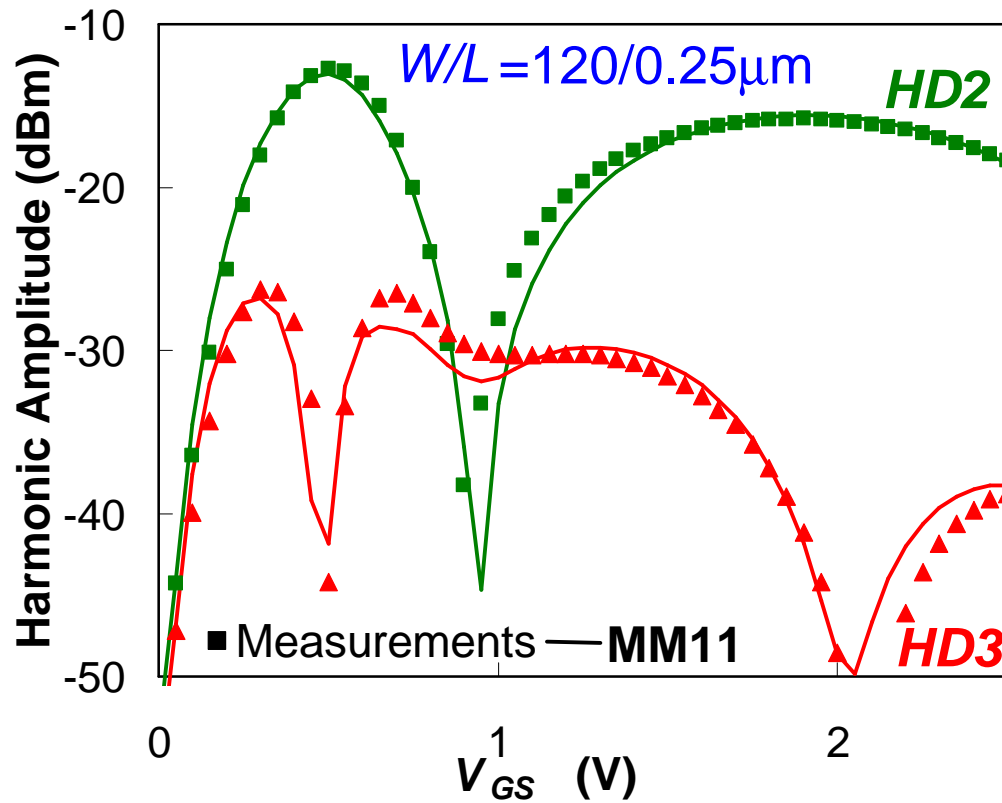
$f=16\text{ MHz}$



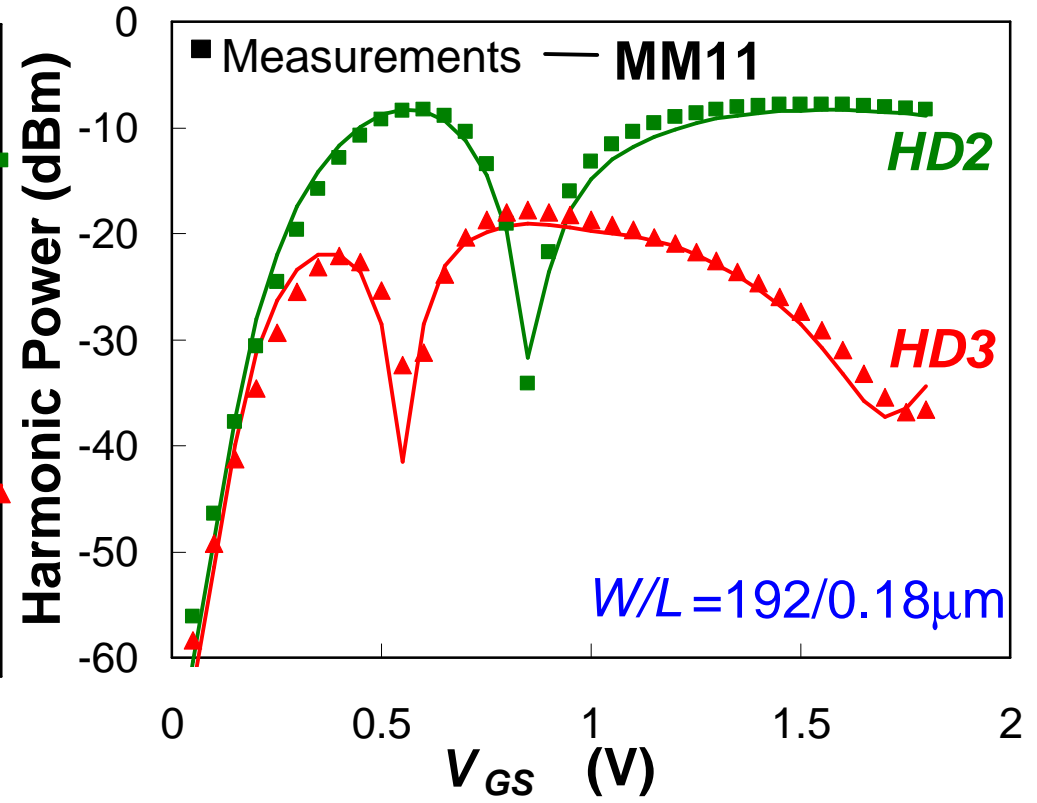
$f=1\text{ GHz}$

# Examples & Applications : RF-Distortion (II)

NMOS,  $f=1\text{GHz}$ ,  $V_{DS}=1.0\text{V}$ ,  $P_{IN}=-5\text{dBm}$



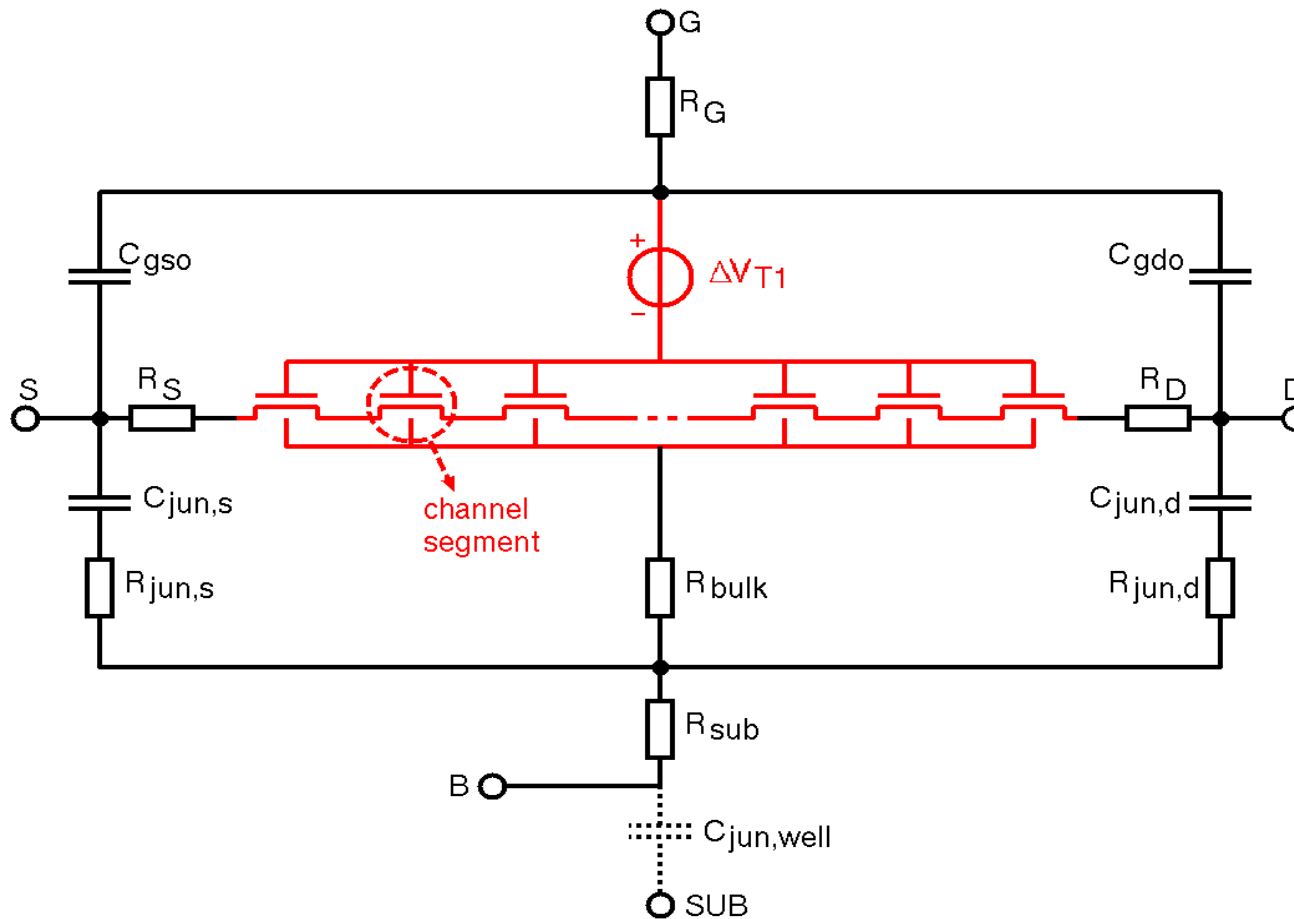
0.25 $\mu\text{m}$  CMOS



0.18 $\mu\text{m}$  CMOS

# Examples & Applications : RF-CMOS Model

NQS-effects described by segmentation model:

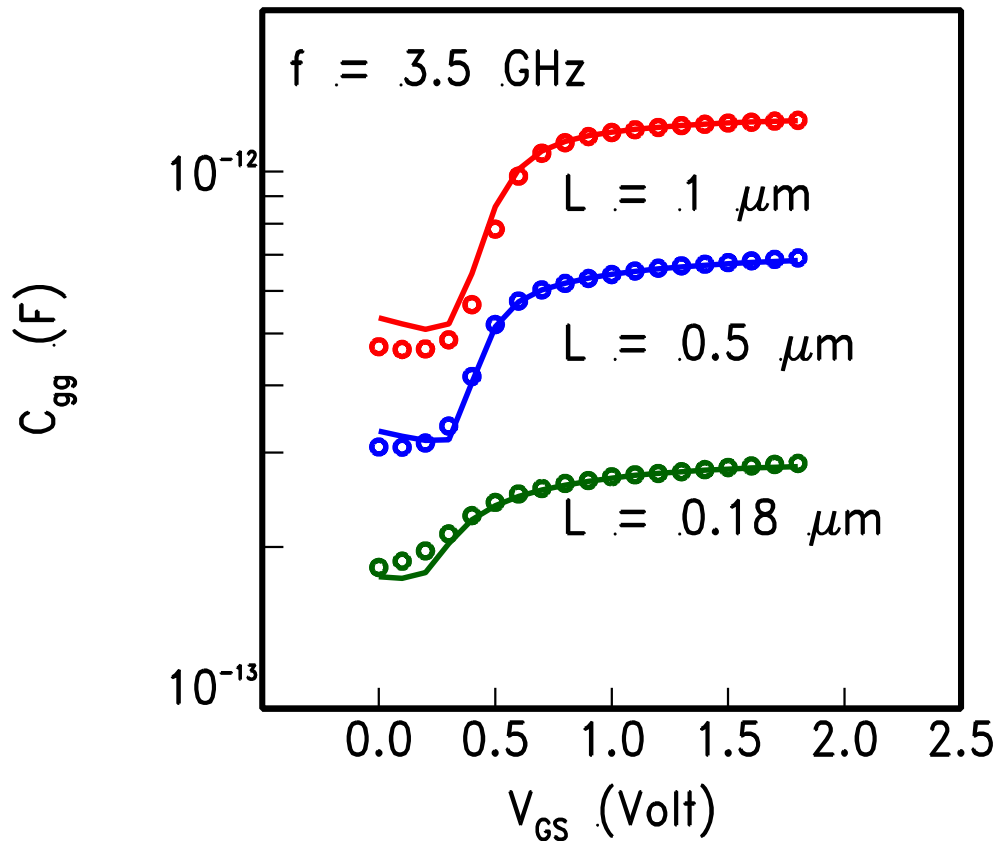


segments have only  
drain current noise  
⇒ induced gate noise  
comes out naturally

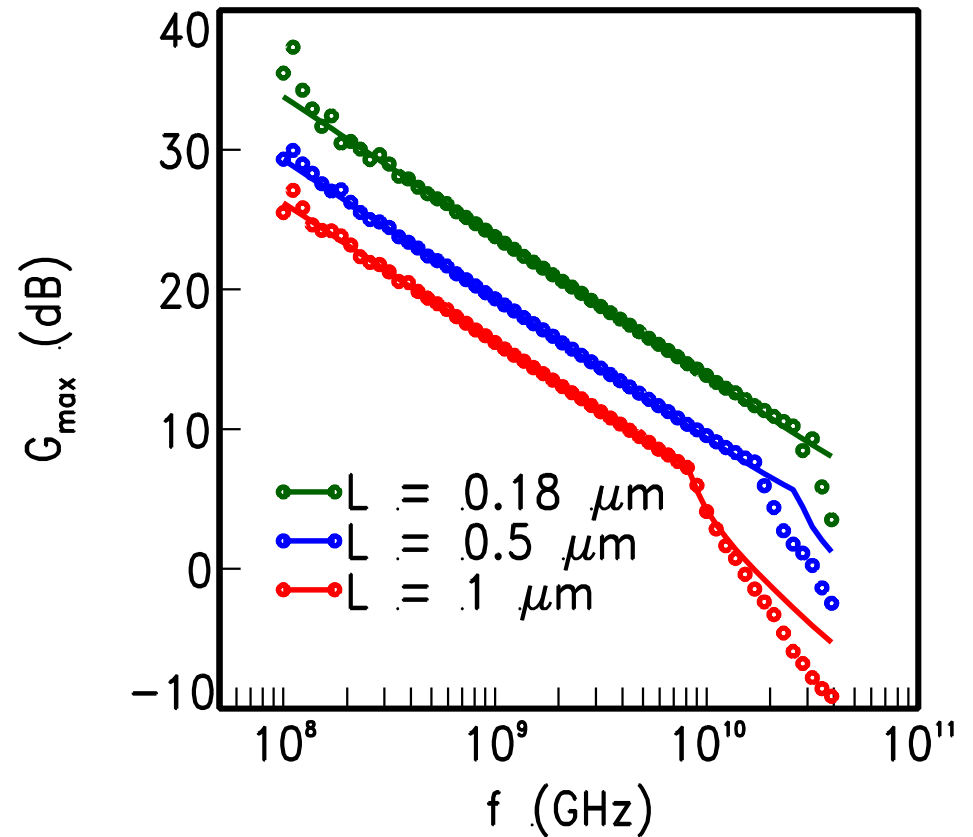
(A.J. Scholten et al.,  
IEDM Tech. Dig.,  
pp.163-166, 1999)

# Examples & Applications : RF-CMOS Model (II)

0.18 $\mu\text{m}$  CMOS, NMOS,  $V_{DS}=1.8\text{V}$  NQS-Model, 5 segments



Input capacitance

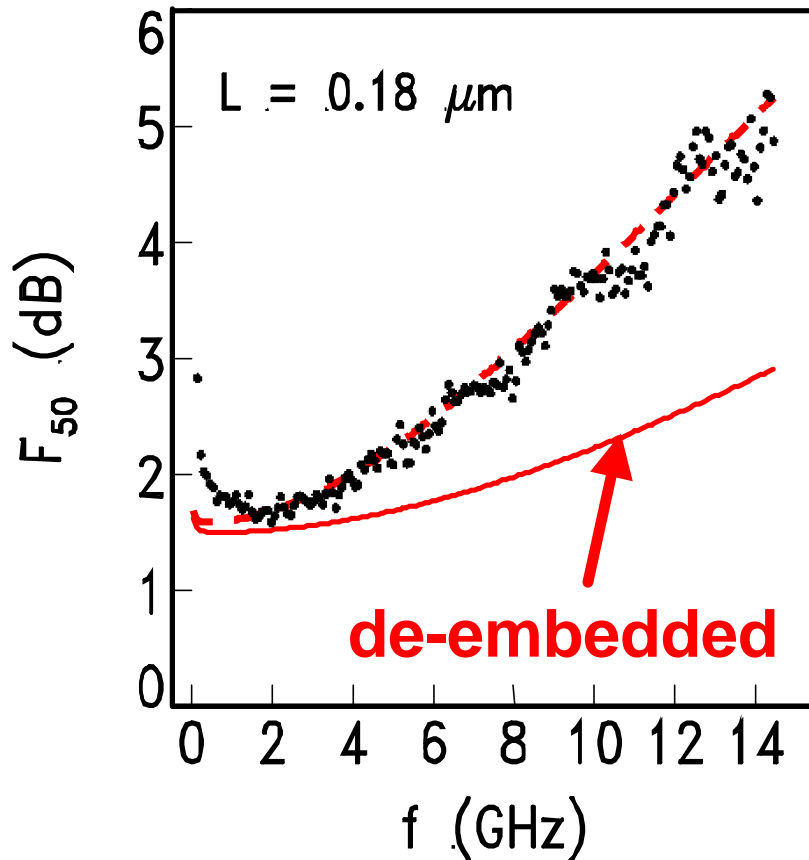


Maximum gain

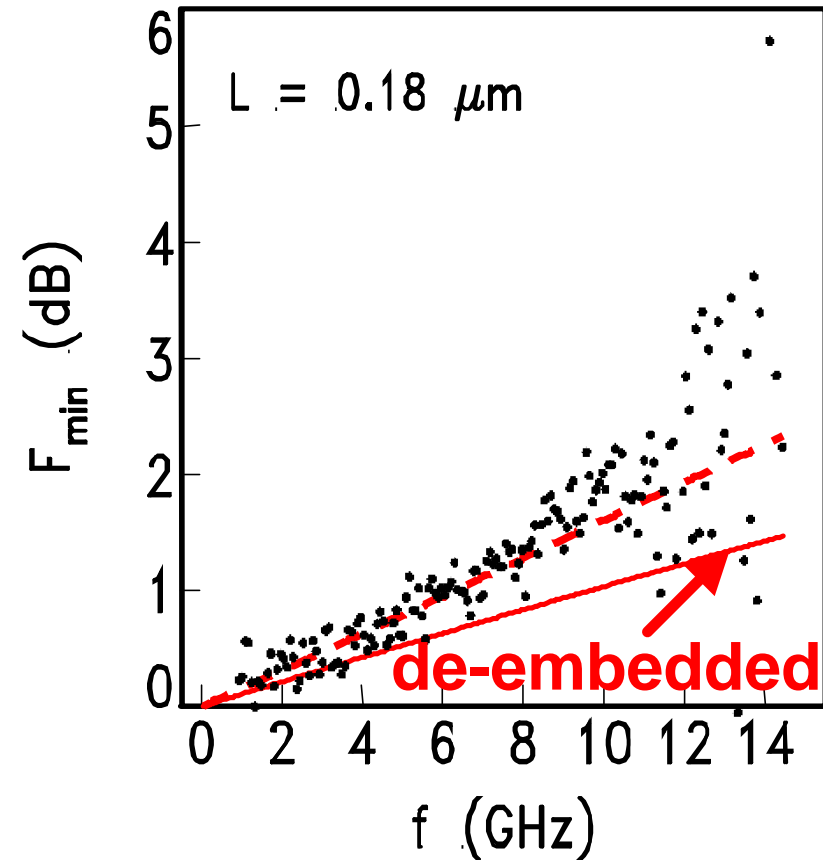
# Examples & Applications : RF-CMOS Model (III)

0.18 $\mu\text{m}$  CMOS, NMOS,  $V_{DS}=1.8\text{V}$

NQS-Model, 5 segments



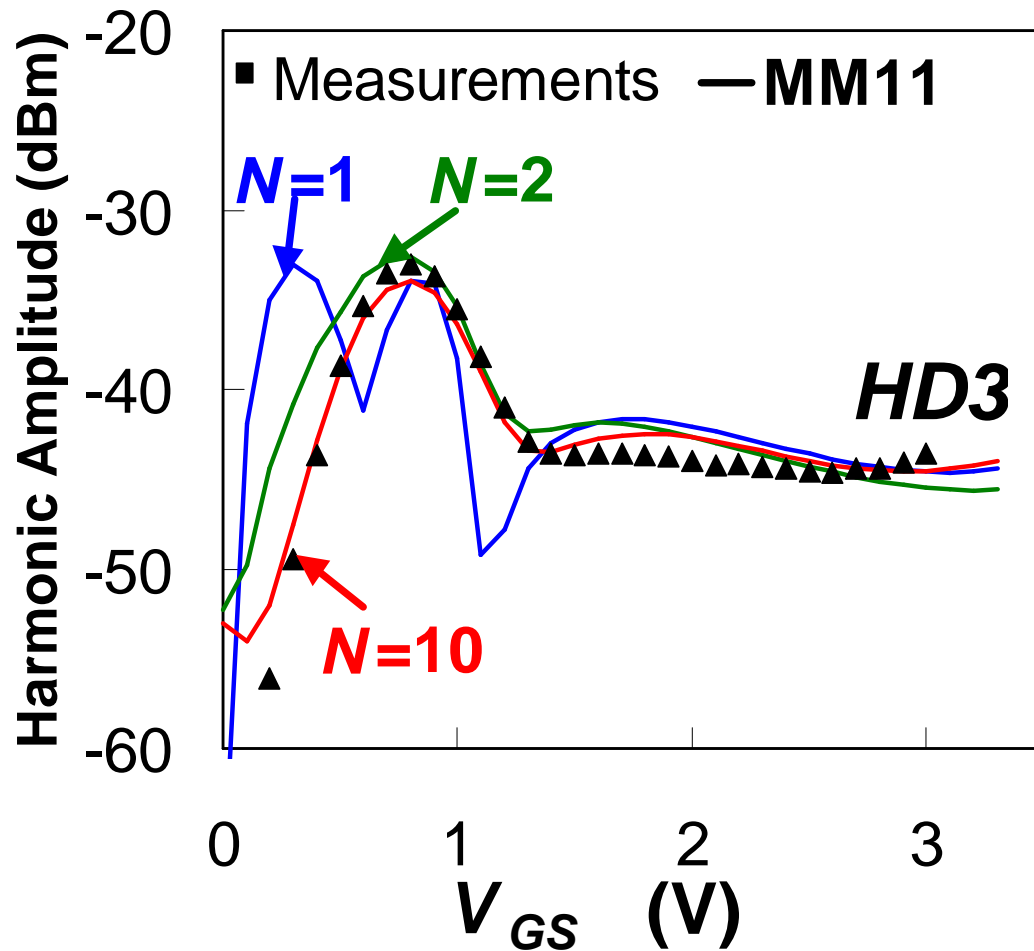
50 $\Omega$  Noise Figure



Minimum Noise Figure

# Examples & Applications : RF-CMOS Model (IV)

NMOS,  $W/L=160/2\mu\text{m}$ ,  $f=1\text{GHz}$ ,  $V_{DS}=3.3\text{V}$ ,  $P_{IN}=0\text{dBm}$



NQS-Model with  $N$  segments

3rd-order distortion

# Conclusions

- MOS Model 11 is a symmetrical,  $y_s$ -based model including accurate description of transconductance, conductance and gate leakage.
- Charge model: accurate description of accumulation, gate depletion, QM-effects and overlap capacitances
- Noise model: accurate description of  $1/f$  noise and thermal noise
- Parameters determined from  $I$ - $V$  and  $C$ - $V$ -measurement
- Model implementation has been finished, first tests on circuits have been performed
- On the Internet (March 2001):  
[http://www.semiconductors.philips.com/Philips\\_Models](http://www.semiconductors.philips.com/Philips_Models)